

Virtual, 27th – 30th September 2021

Development of LGADs and 3D detectors at FBK

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Detectors for 4D Tracking in High-Energy Physics

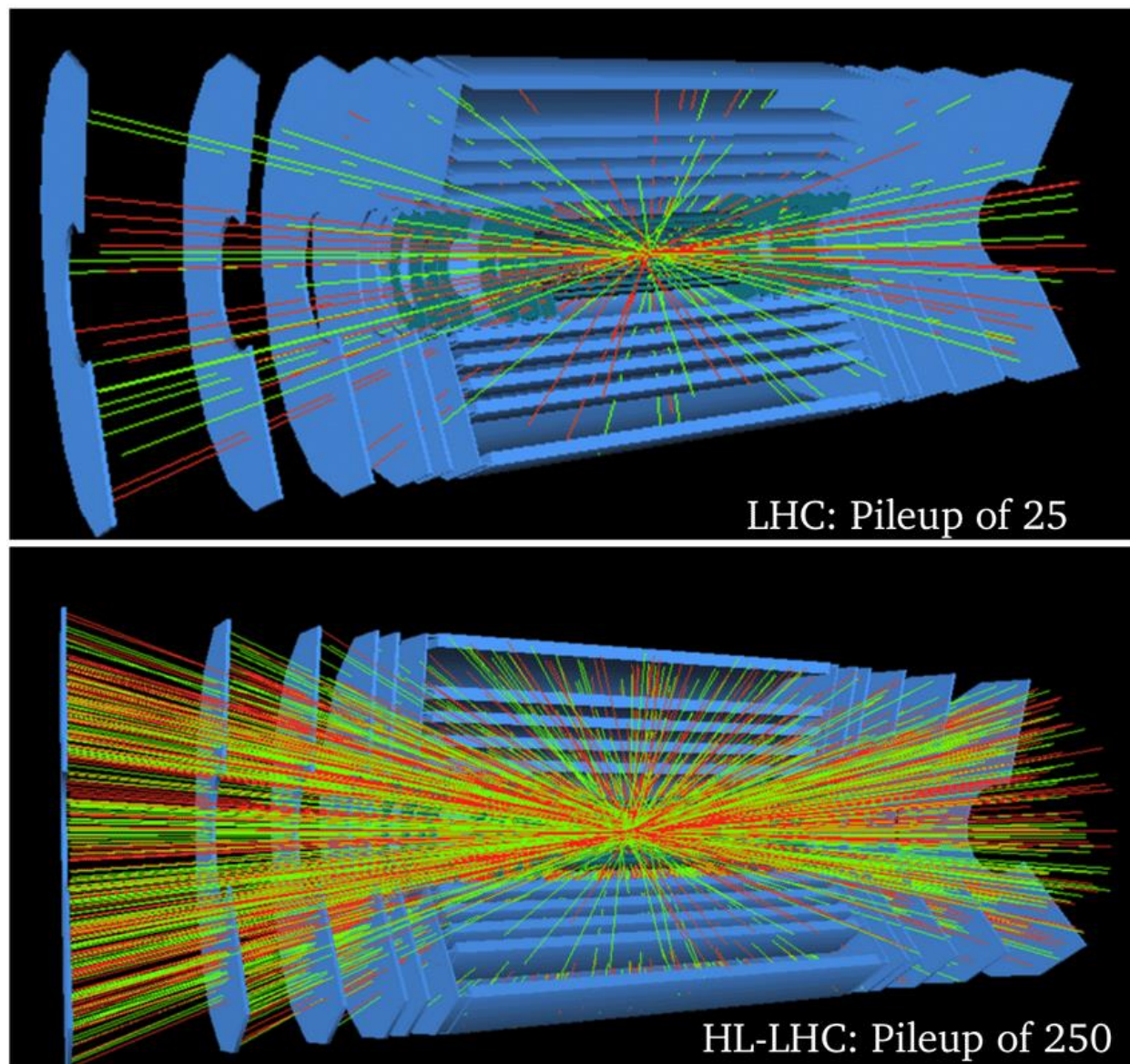


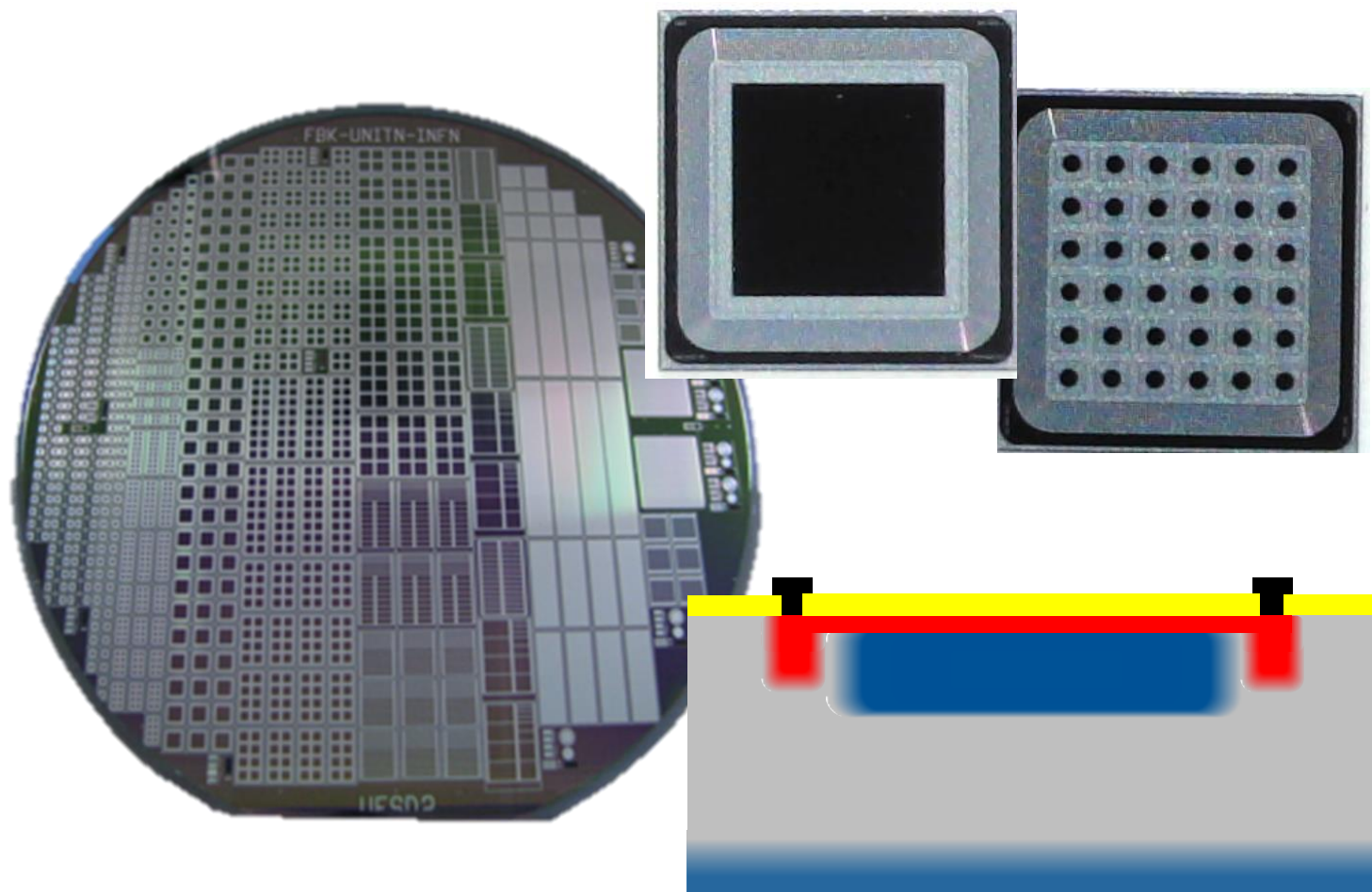
Image from: “Development and evaluation of novel, large area, radiation hard silicon microstrip sensors for the ATLAS ITK experiment at the HL-LHC” Hunter, R.F.H.. (2017)

Particle tracking in HEP experiments

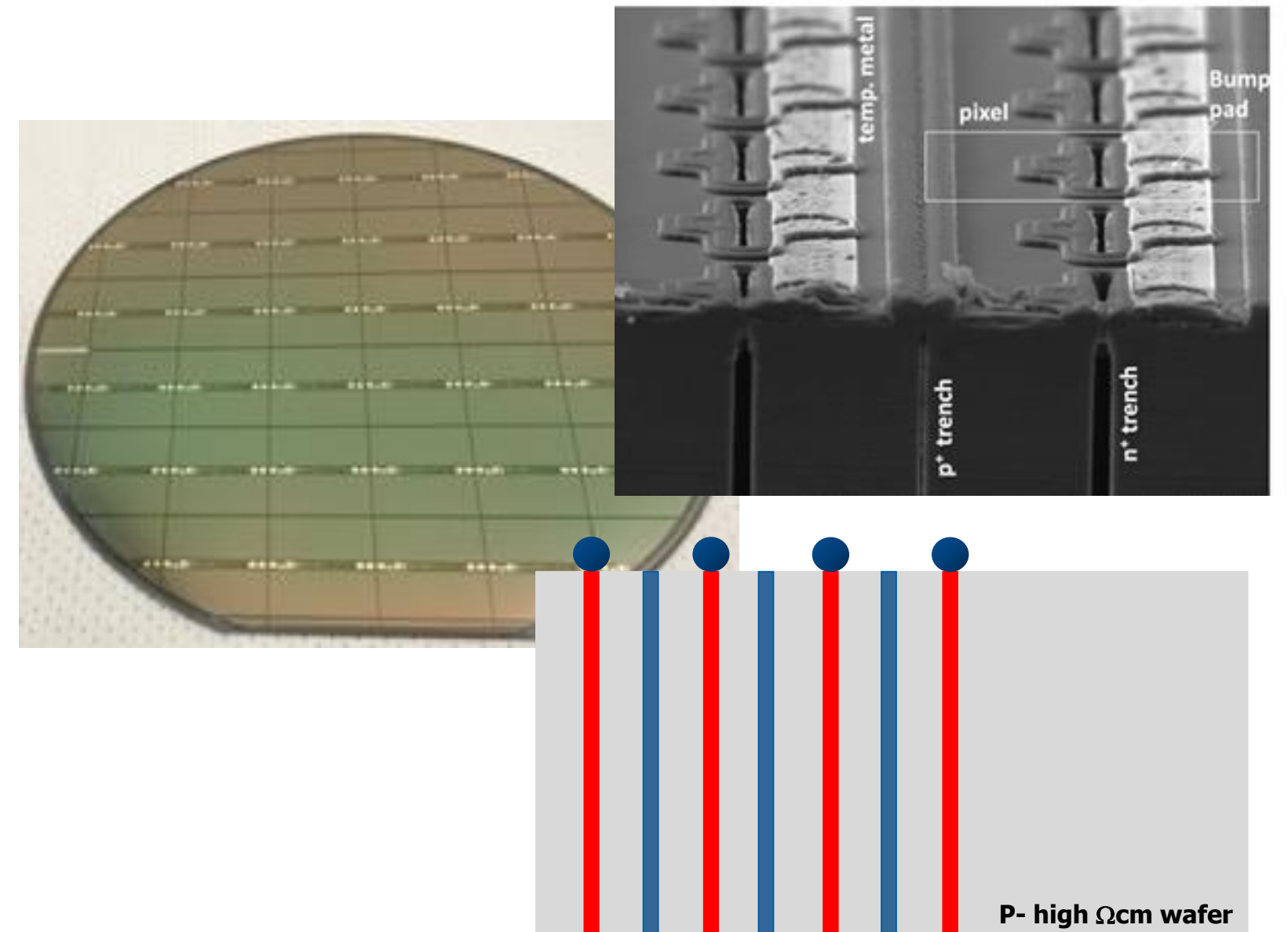
- High Luminosity LHC (HL-LHC, operational in 2025) [1,2]:
 - Luminosity: x5 compared to LHC → 150-200 events per bunch crossing
 - Timing and spatial resolution of standard silicon tracking sensors not sufficient: *10-15% of vertexes composed of 2 events*
- Requirements for silicon timing detectors in HL-LHC:
 - Timing resolution: *30 ps (rms)*
 - Low spatial granularity: *~1 mm* (timing information assigned to the track)
 - High radiation hardness: *$> 1 \cdot 10^{15} n_{eq} \cdot cm^{-2}$*
- Real 4D tracking detectors required for future colliders (CLIC, FCC, etc.) [3]:
 - Timing resolution: *~10 ps (rms)*
 - High spatial granularity: *~10 μm*
 - High radiation hardness: *$> 1 \cdot 10^{16/17} n_{eq} \cdot cm^{-2}$*

Detectors for 4D Tracking in High-Energy Physics

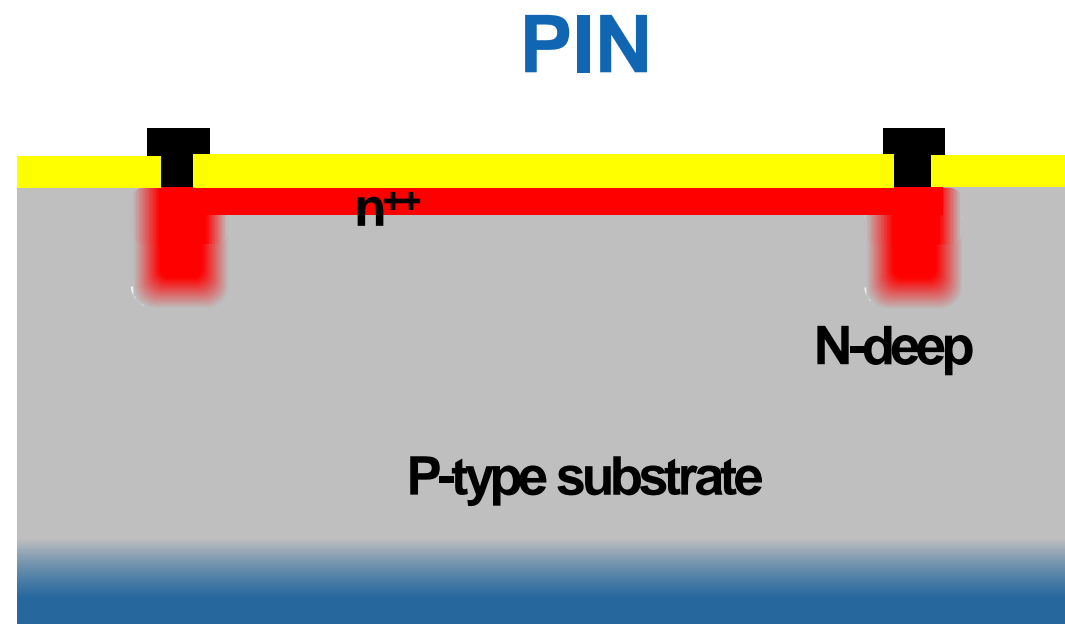
Low Gain Avalanche Diode



3D Detectors

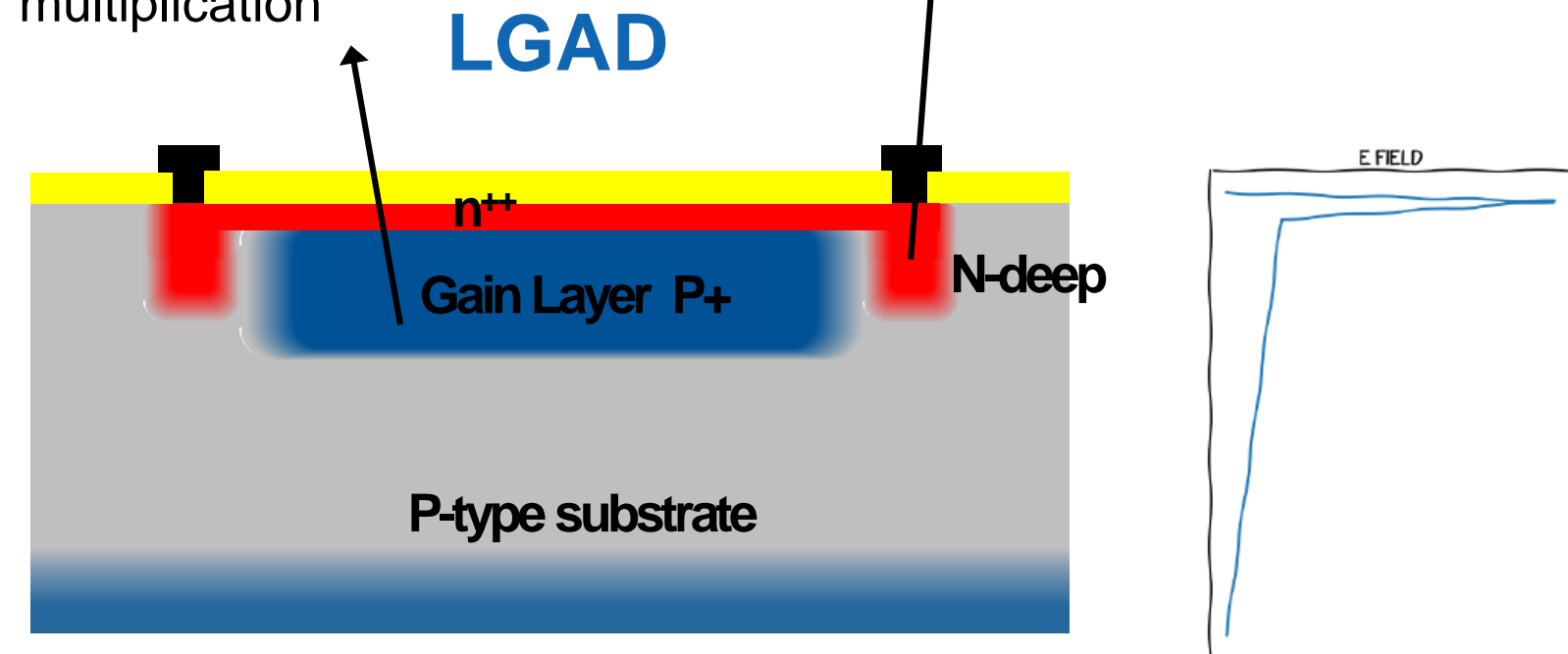


LGAD Technology



High-Field region: Electric Field $> 2 \times 10^5$ V/cm to activate the impact ionizing multiplication

Junction Termination Edge: controls the Electric Field at the border region



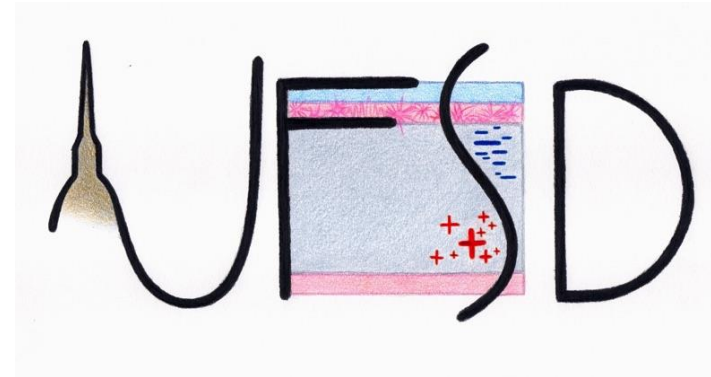
- Traditional silicon sensors cannot fulfill some of the requirements:

- Standard PiN diode sensors (pixels/microstrips): limited timing resolution (~ 200 ps)
- APDs: excessive shot noise

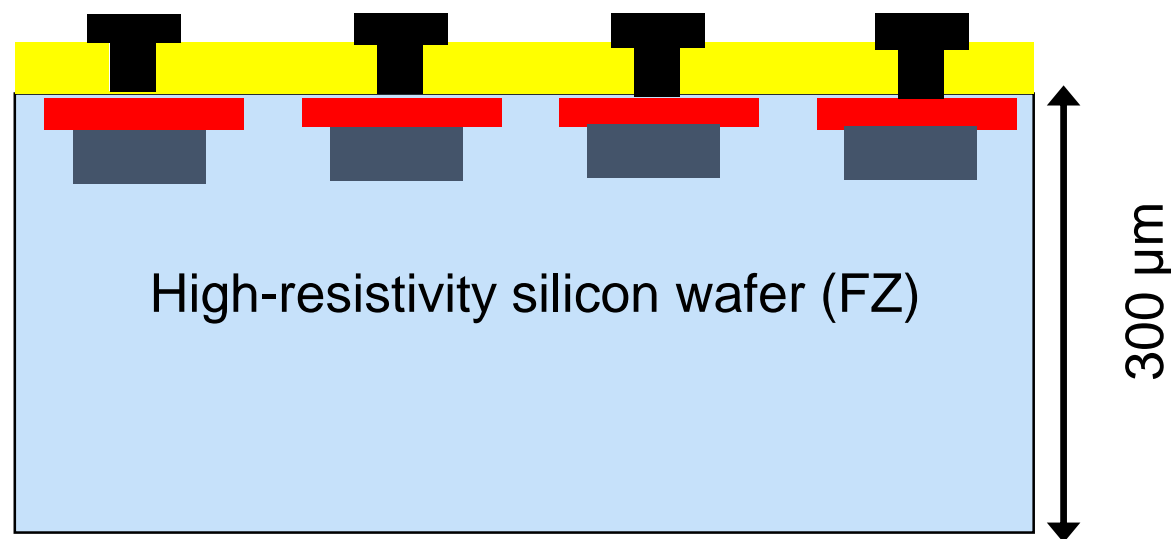
- LGAD detectors:

- n^{++}/p junction + a p^+ enrichment region
- Low gain (~ 10) \rightarrow Reduced excess noise factor
- Uniform weighting field (large pad area) \rightarrow homogeneous time response

LGAD for Timing



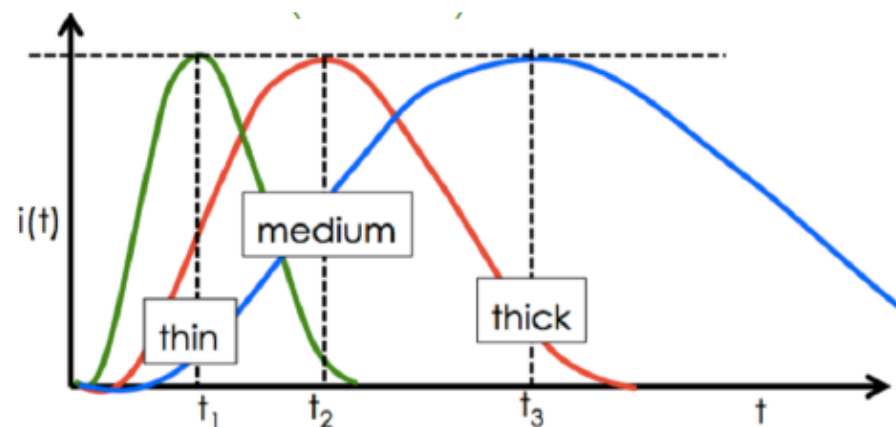
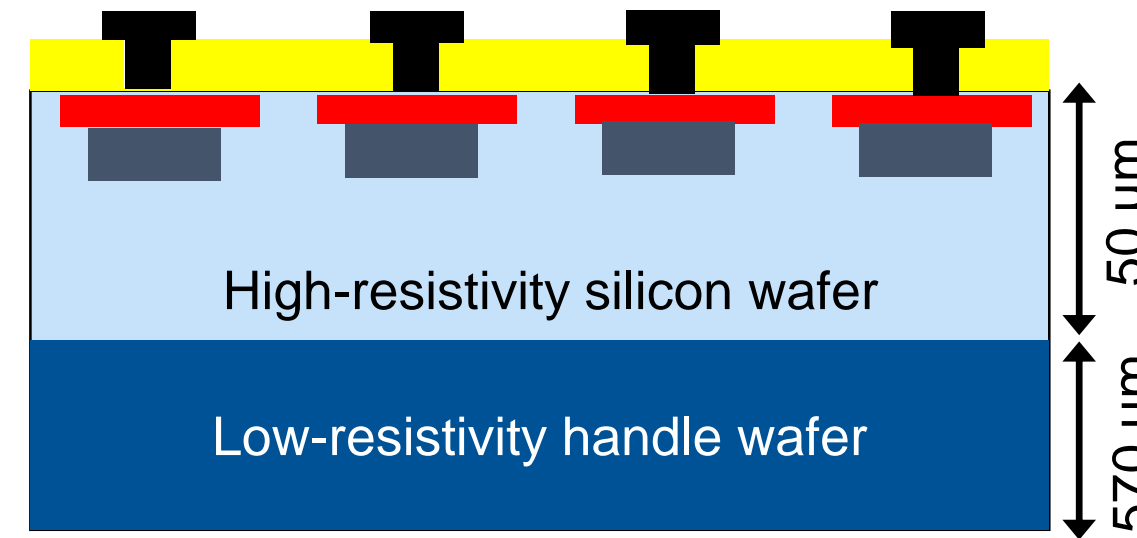
Thick LGAD (2015/2016)



go thin



Thin LGAD (>2016)



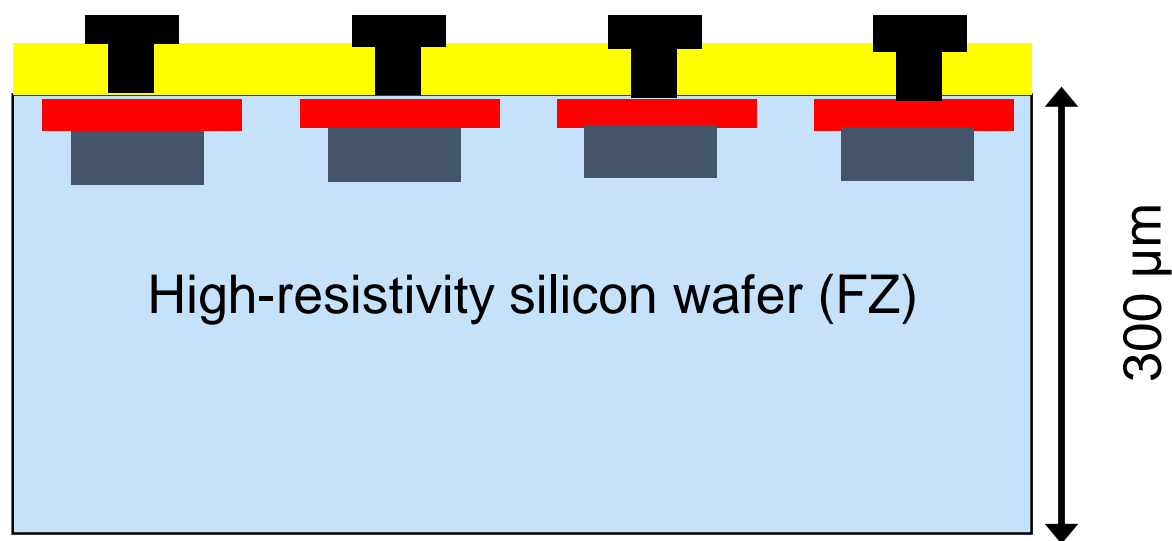
N. Cartiglia

$$dV/dt \sim \frac{di_{gain}}{dt} \propto \frac{G}{d}$$

- Reduced thickness (50 μm) → Increase slew rate of the signal
- Uniform weighting field (large pad area) → homogeneous time response
- Saturated drift velocity (Efield > 30 kV·cm⁻¹) → Reduce jitter

LGAD for Timing

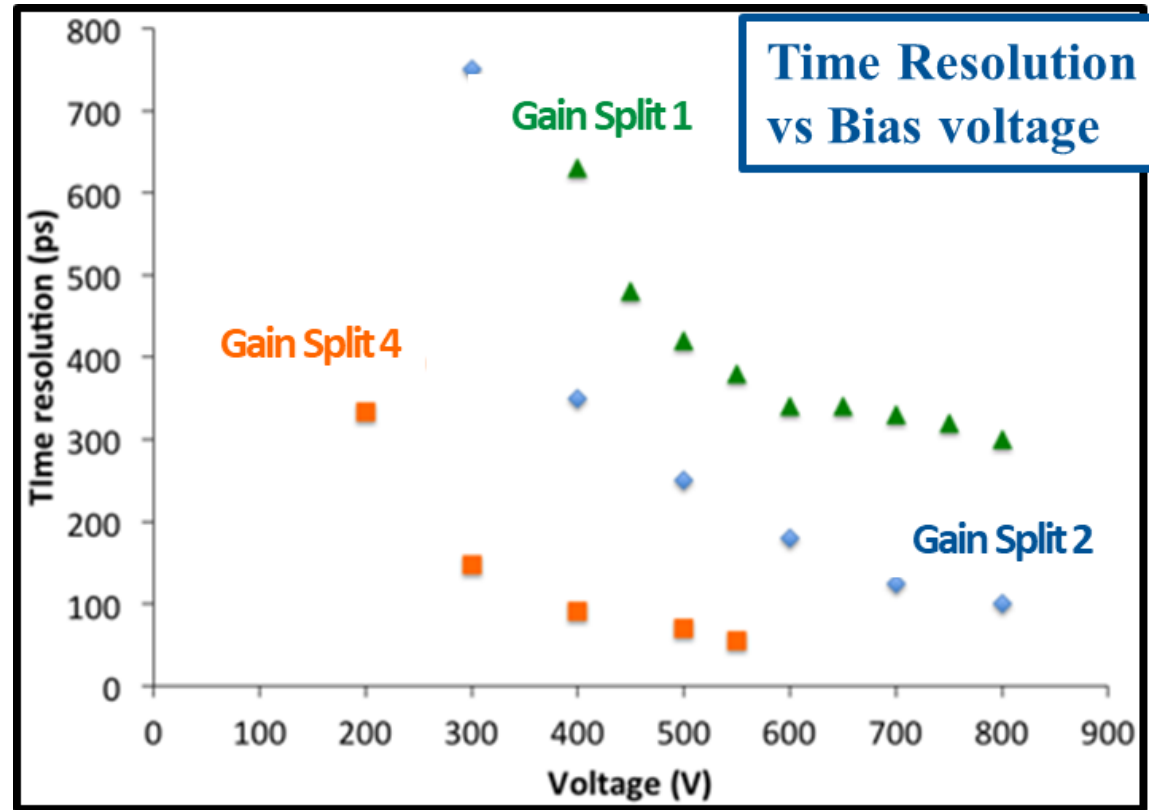
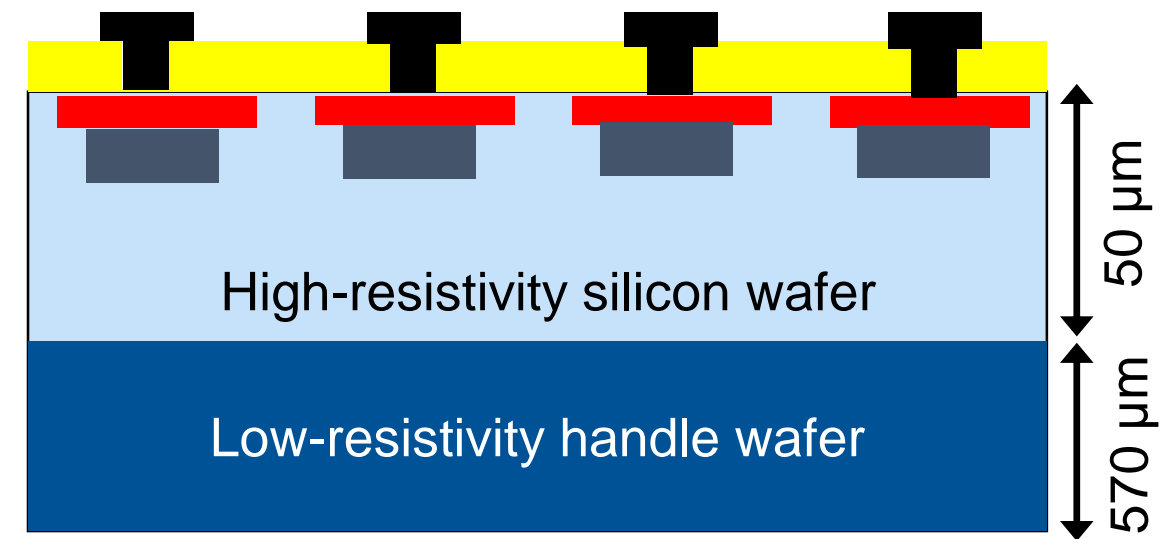
Thick LGAD (2015/2016)



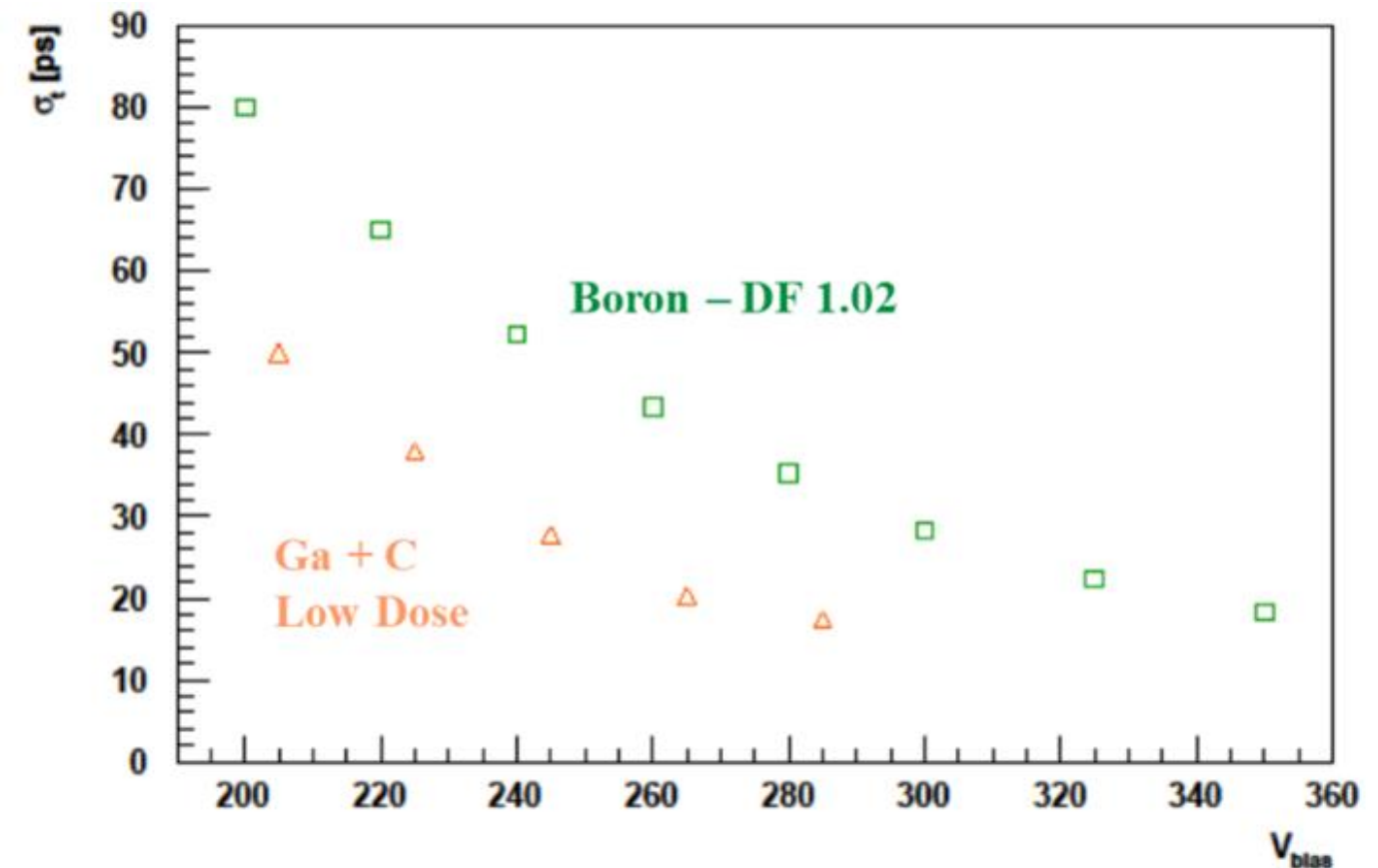
go thin



Thin LGAD (>2016)



Time jitter (not-irradiated)

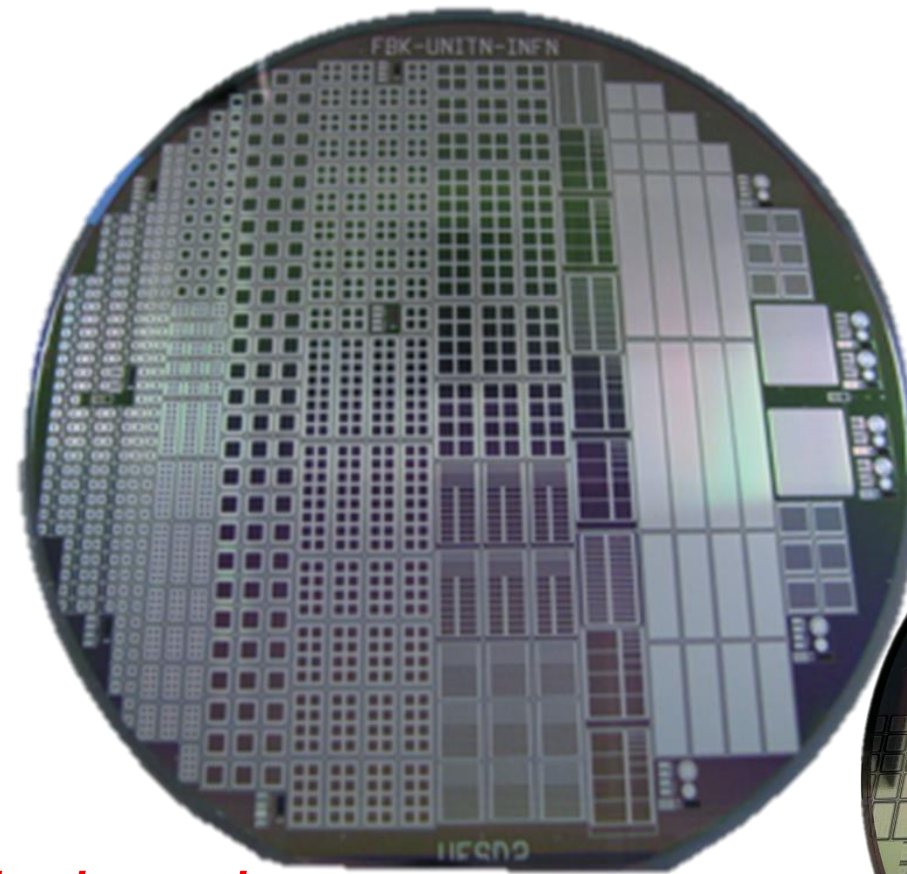


LGAD Fabrication Technology

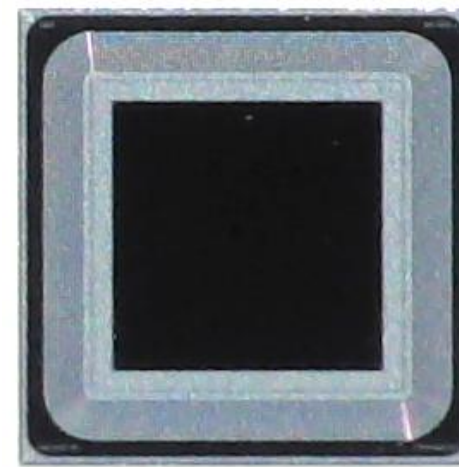
- Fabricated on 6 inches Wafers
- Custom CMOS-like Technology
- Fabricated in the FBK internal facility (ISO 9001:2015 certified)



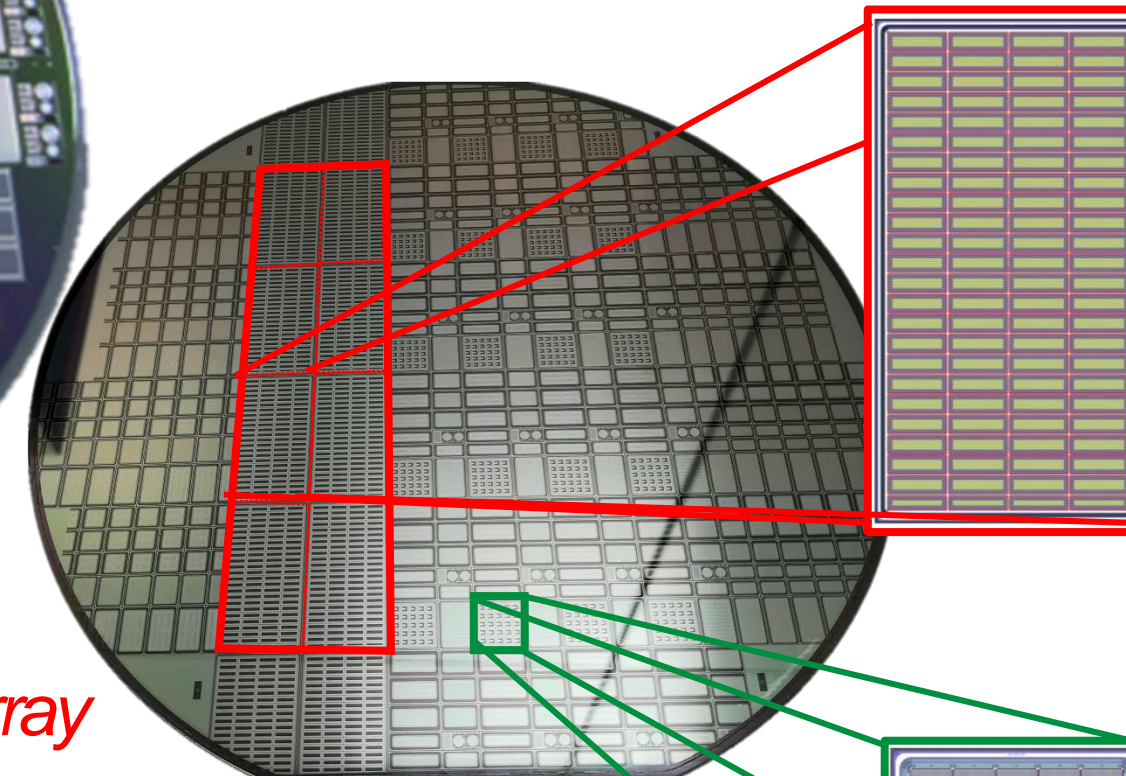
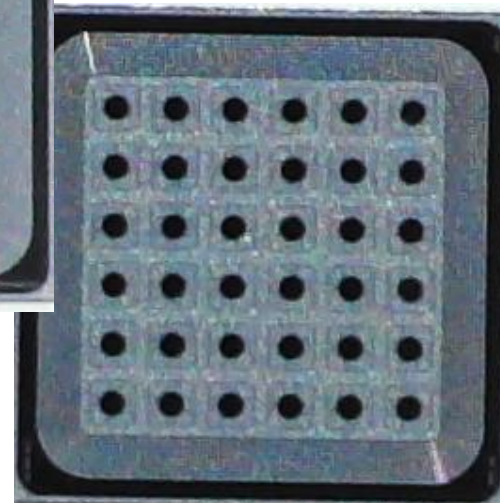
Single pads,
Pad arrays;
Strips;
Other pixelated detectors....



Single pad



Pixel Array



CMS ROC

Pad: $3 \times 1 \text{ mm}^2$
Array 4×24 pads
Array Size: $13.2 \times 25.0 \text{ mm}^2$

8 full arrays per Wafer

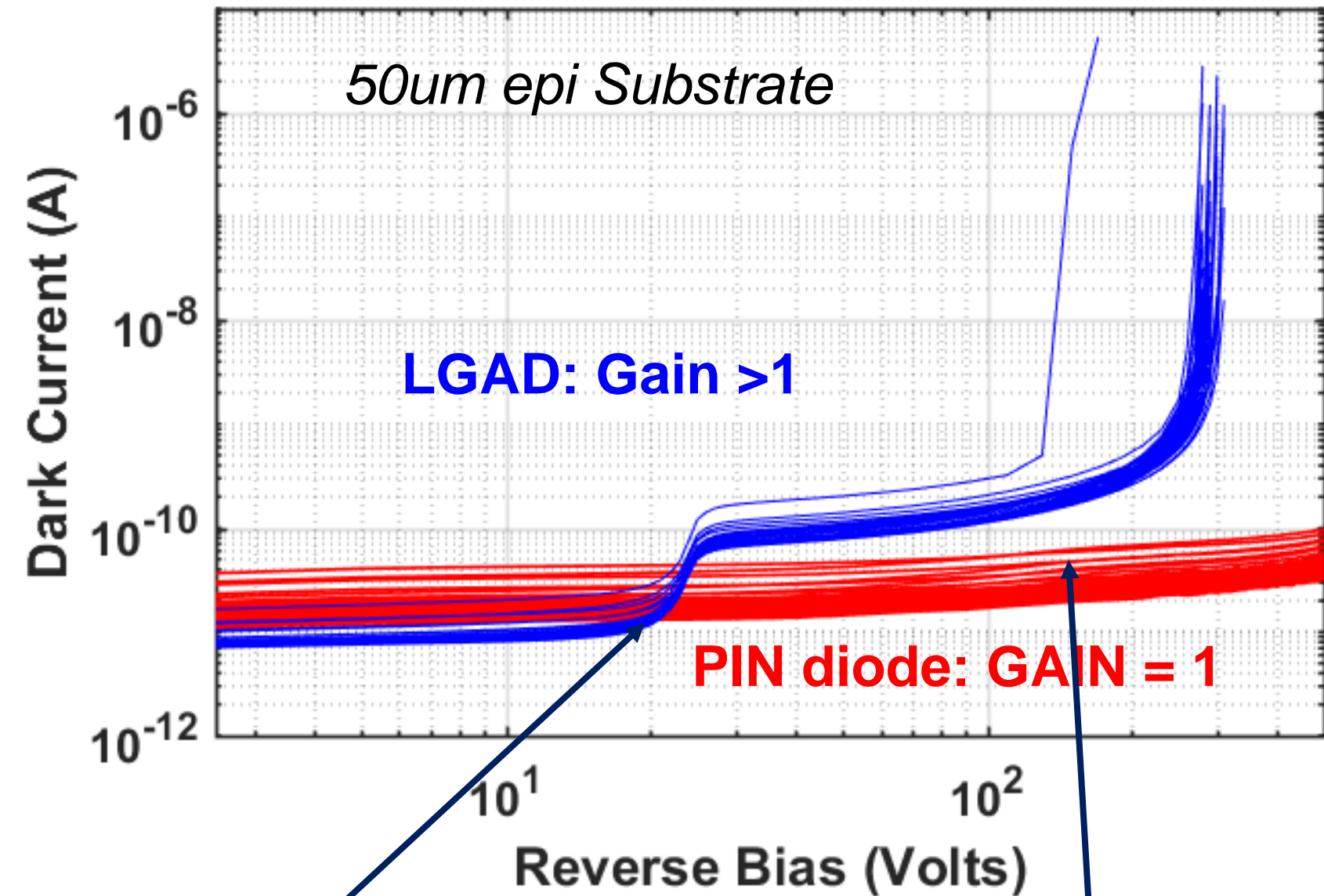
ATLAS ALTIROC

Pad: $1.3 \times 1.3 \text{ mm}^2$
Array 5×5 pads
Array Size: $8.0 \times 8.0 \text{ mm}^2$

20 full arrays per Wafer

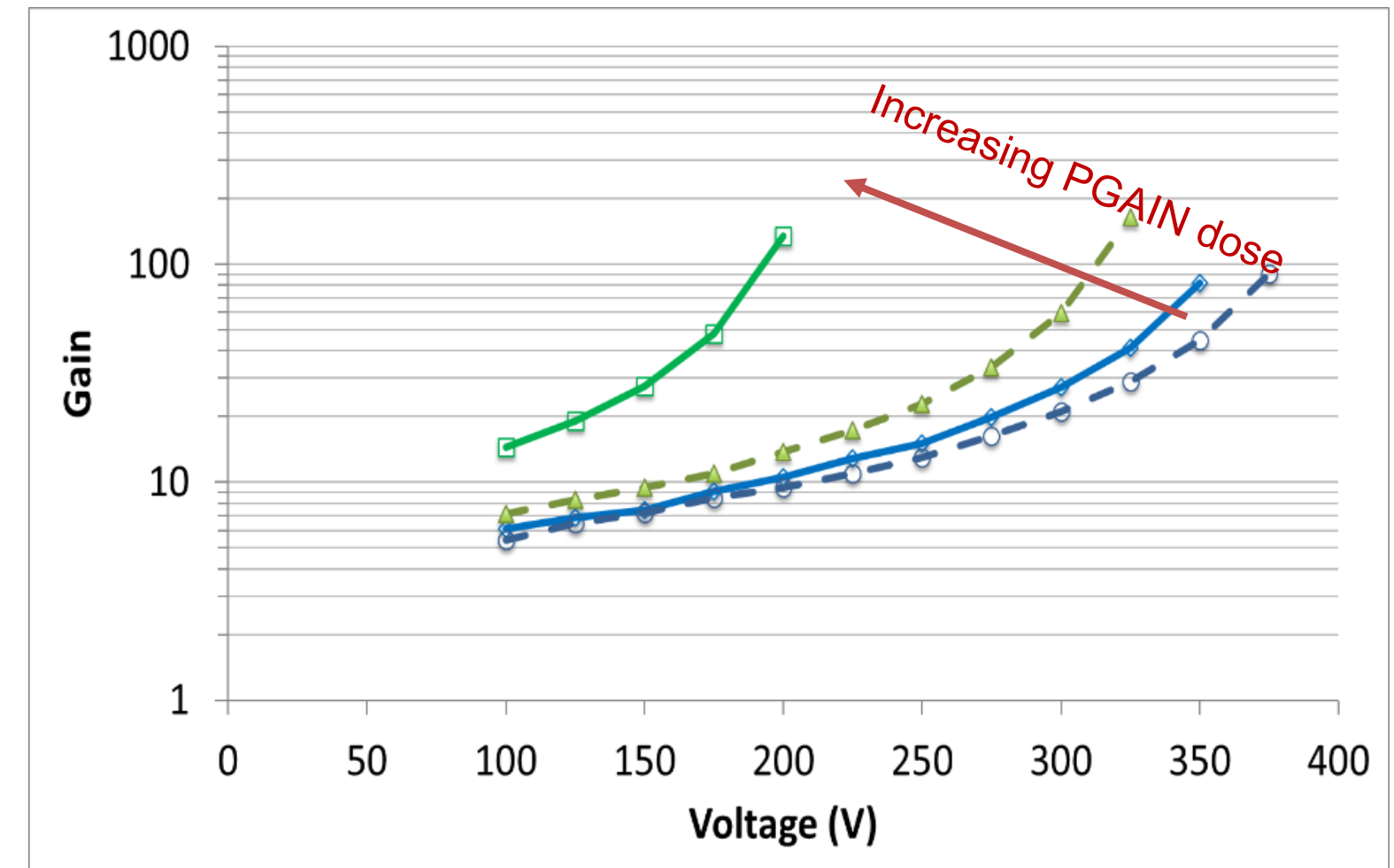
LGAD Fabrication Technology

UFSD and PIN 1mm² pads I-V curves



gain layer
depletion Voltage

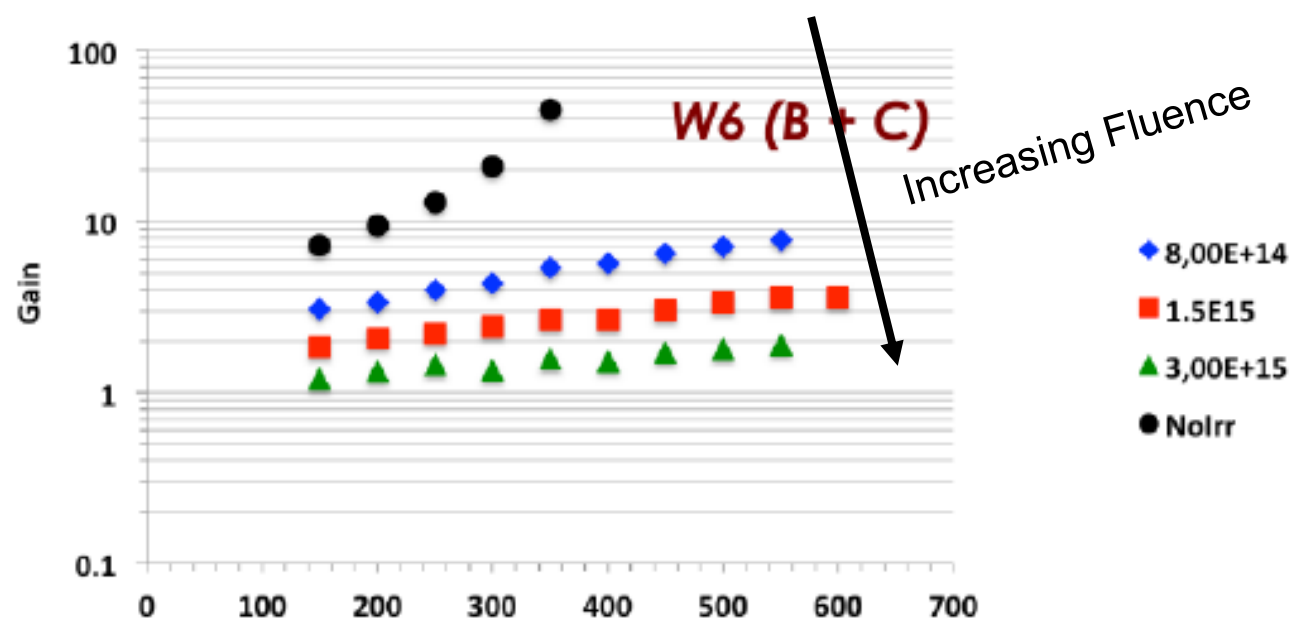
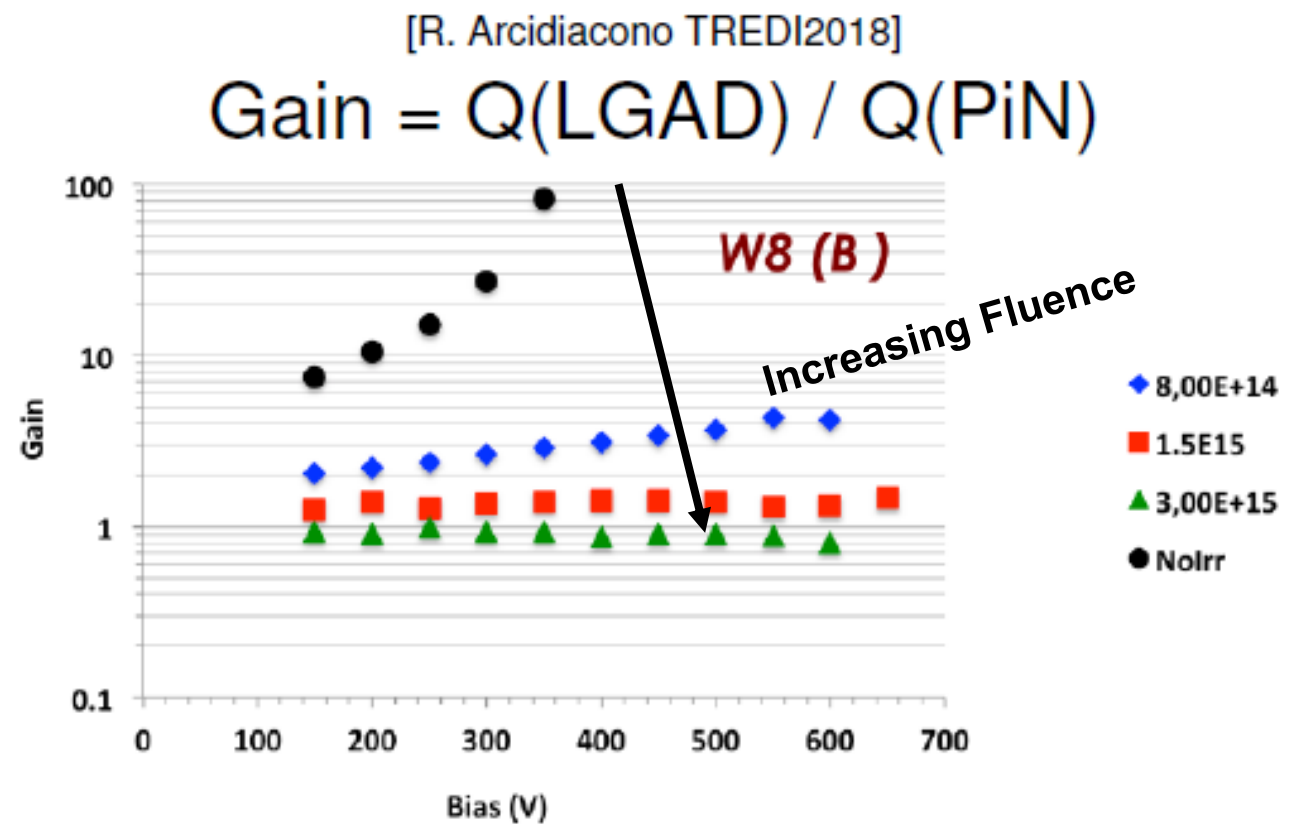
The Gain increases with the Voltage up to the Breakdown



- The Detector Gain depends on:
 - implantation dose of the Gain layer
 - Bias Voltage
- Samples with higher dose have higher gain at lower Voltage

LGAD – Radiation hardness

Problem: Radiation level de-activate the dopant of the gain layer, reducing the effective gain after irradiation (**Initial Acceptor Removal Effect**) [M. Moll, Vertex 2019]



- After irradiation the Gain of LGADs is reduced
- Gain is completely lost after $1e15 \text{ neq/cm}^2$
- It is possible to partially compensate the gain-loss by increasing the bias voltage

- We demonstrated that the inclusion of some chemical impurities (like Carbon) in the silicon lattice is effective in mitigating this effect

LGAD – Radiation hardness

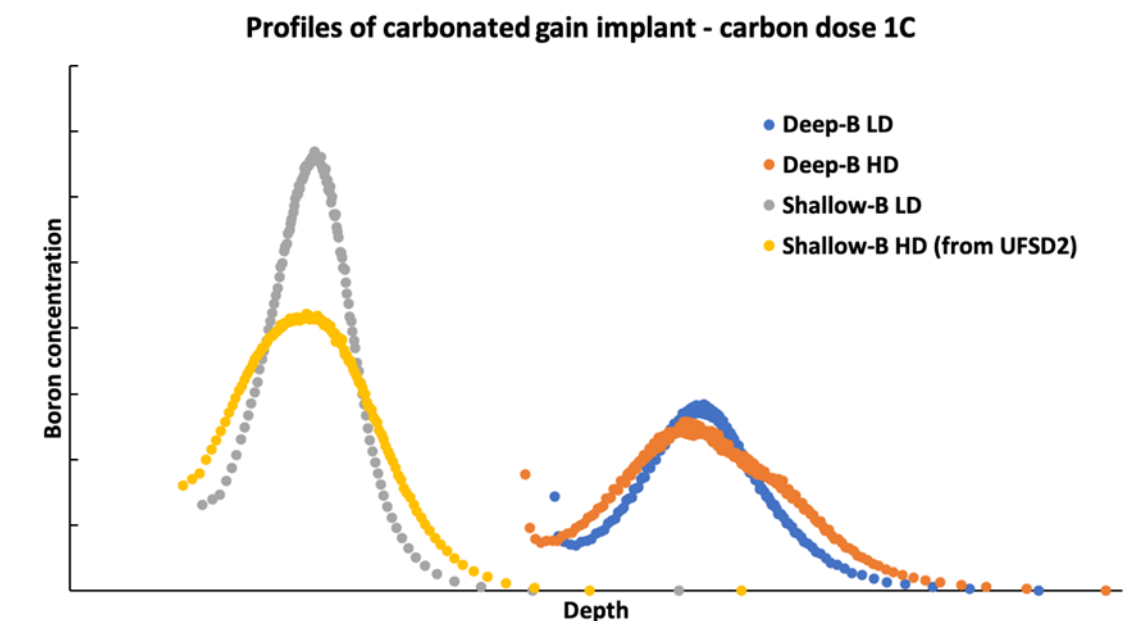
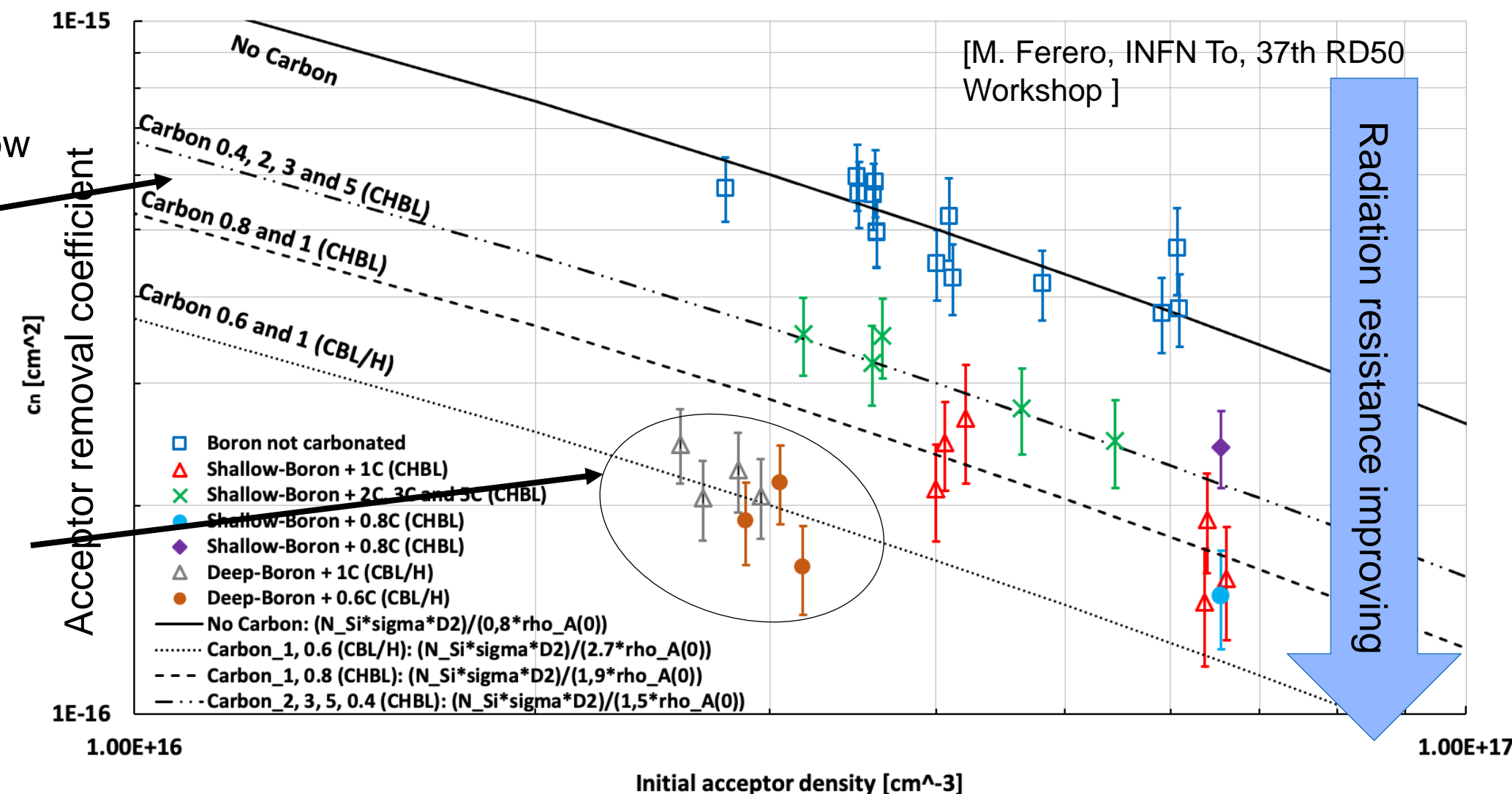
Acceptor removal parametrization (M. Ferrero and N. Cartiglia)

$$\frac{N_B(\phi)}{N_B(0)} = e^{-c\phi} \quad c(N_B) = \frac{N_{Si} * \sigma_{Si} * D_2}{k_{param.} * N_B(0)}$$

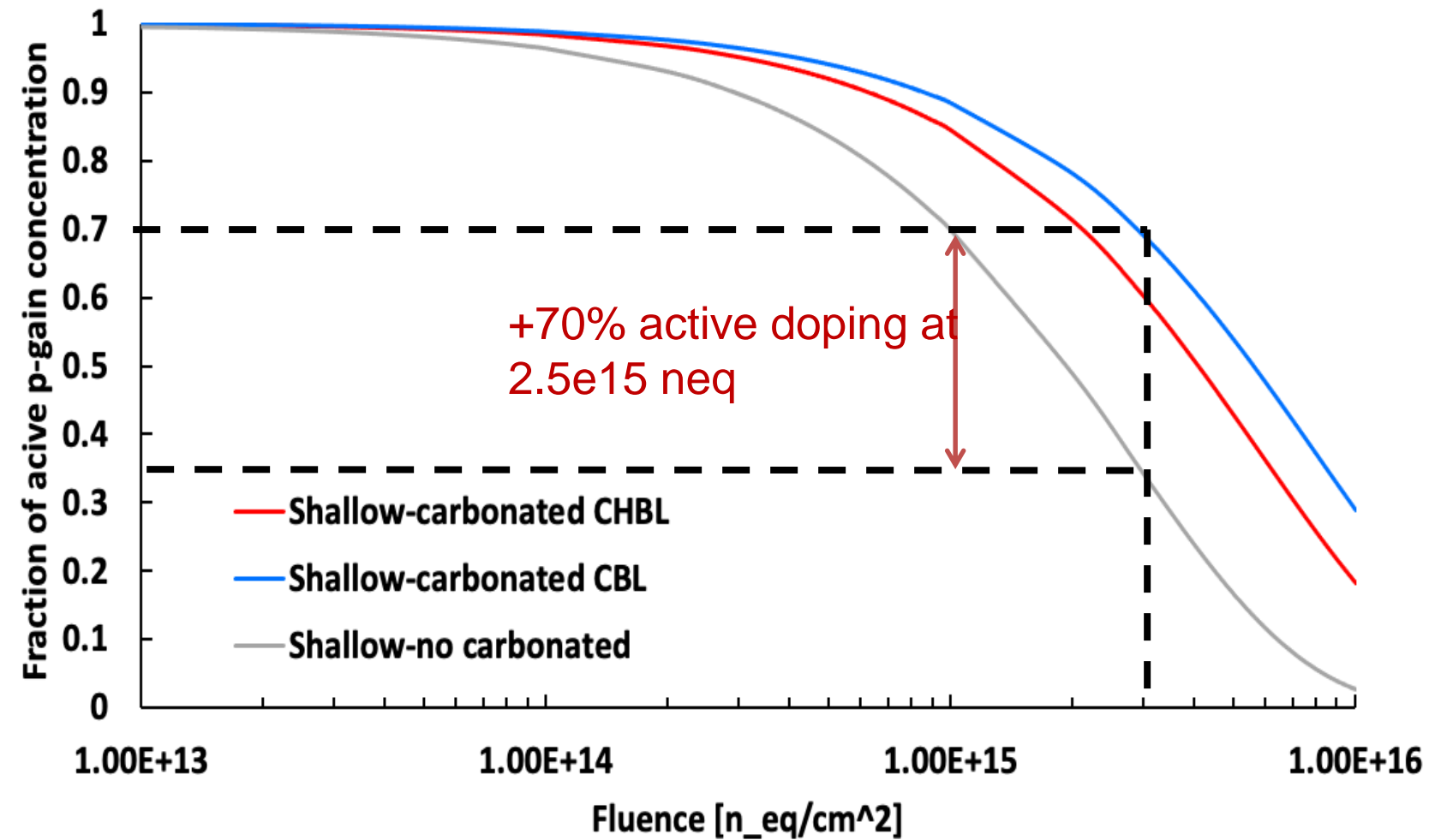
Carbon co-implantation Optimization

- Carbon Dose
- Boron Implantation (PGAIN) Depth
- Boron/Carbon Activation and Diffusion
- Boron Profile and peak concentration

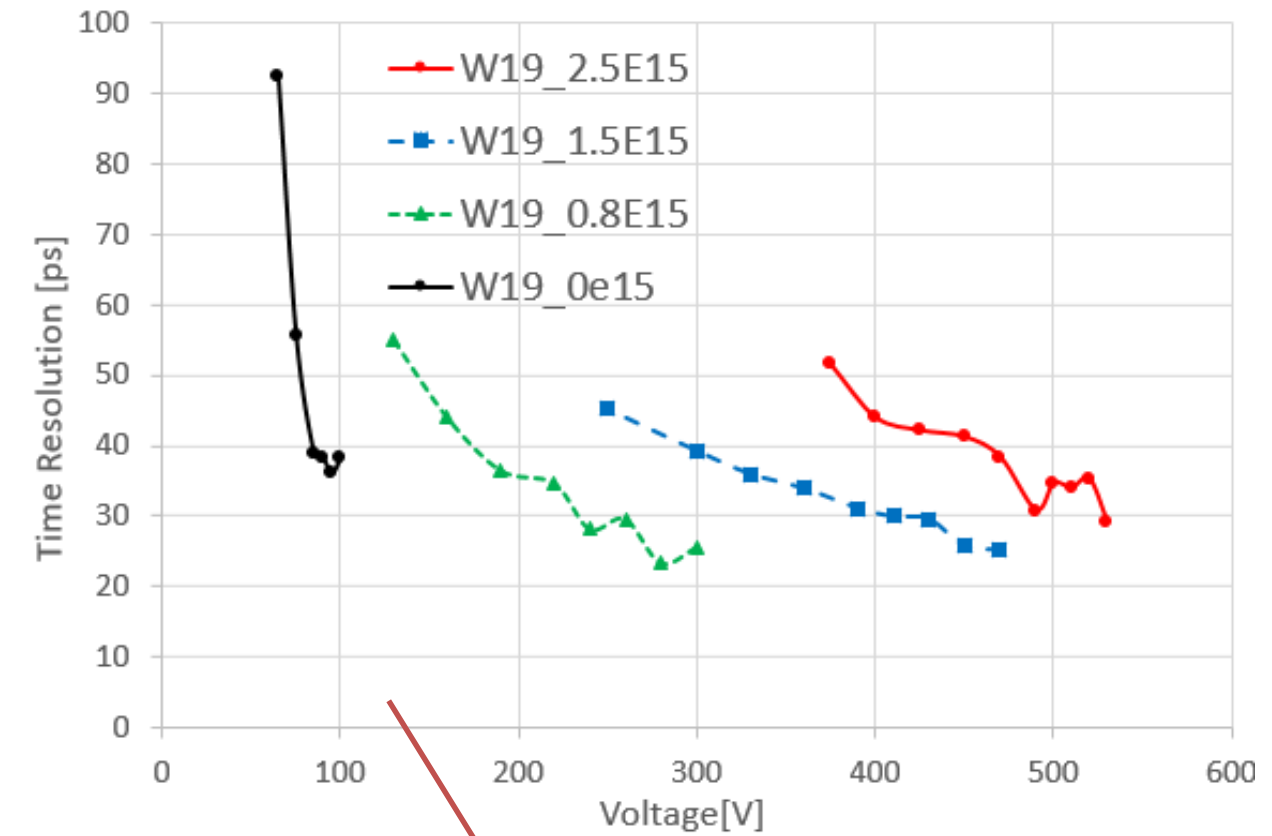
Acceptor Removal parametrization - neutrons



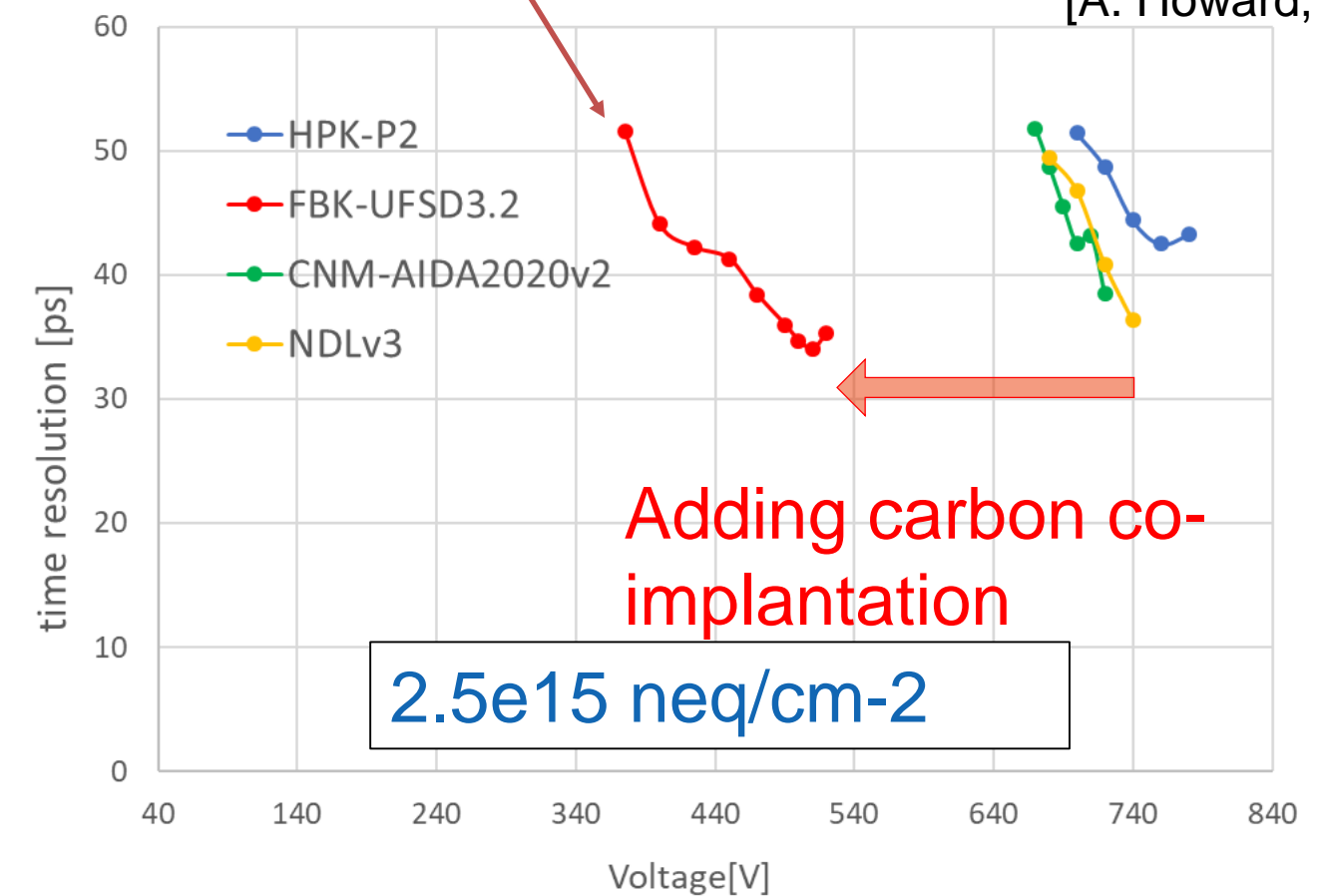
LGAD – Radiation hardness



- Carbon co-implantation allows to reach an exceptional time resolution (~ 30 ps) after irradiation ($2.5e15$ cm^{-2} neq) using about 300 Volts less wrt not carbonated samples.



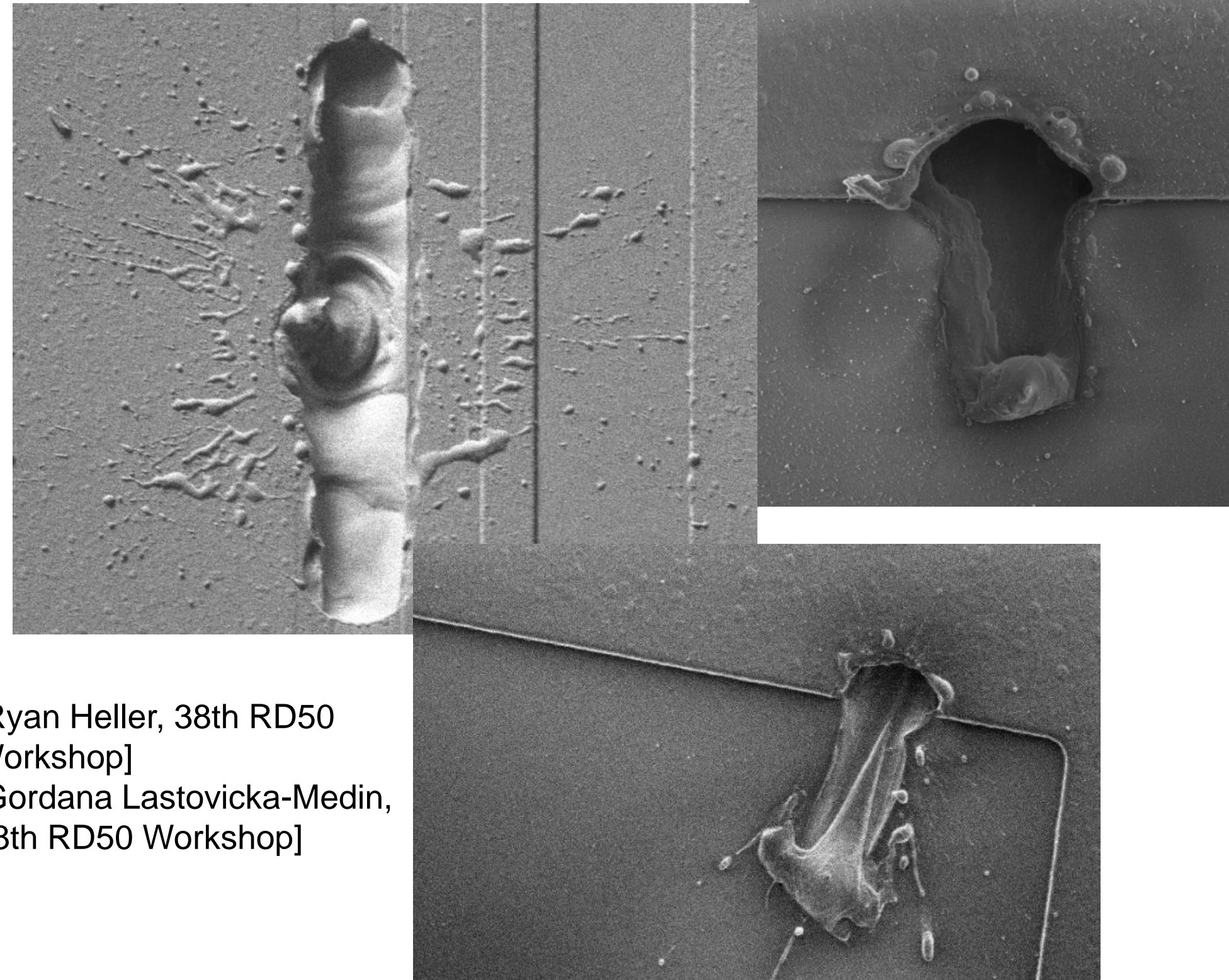
[A. Howard, 37th RD50 Workshop]



LGAD – Radiation hardness

LGAD Mortality during Test Beam

- There is an evidence for death of highly irradiated LGADs at test beam
- Probably due to a rare, large ionization events producing large current in narrow path
- Mortality is function of sensor thickness and voltage only (Gain is not necessary for death mechanism)
- Fatal voltage: $> 600\text{V}$ for $50\ \mu\text{m}$ Sensors
- Carbon co-implantation (lower operative bias) or using thicker substrates reduce the sensor mortality

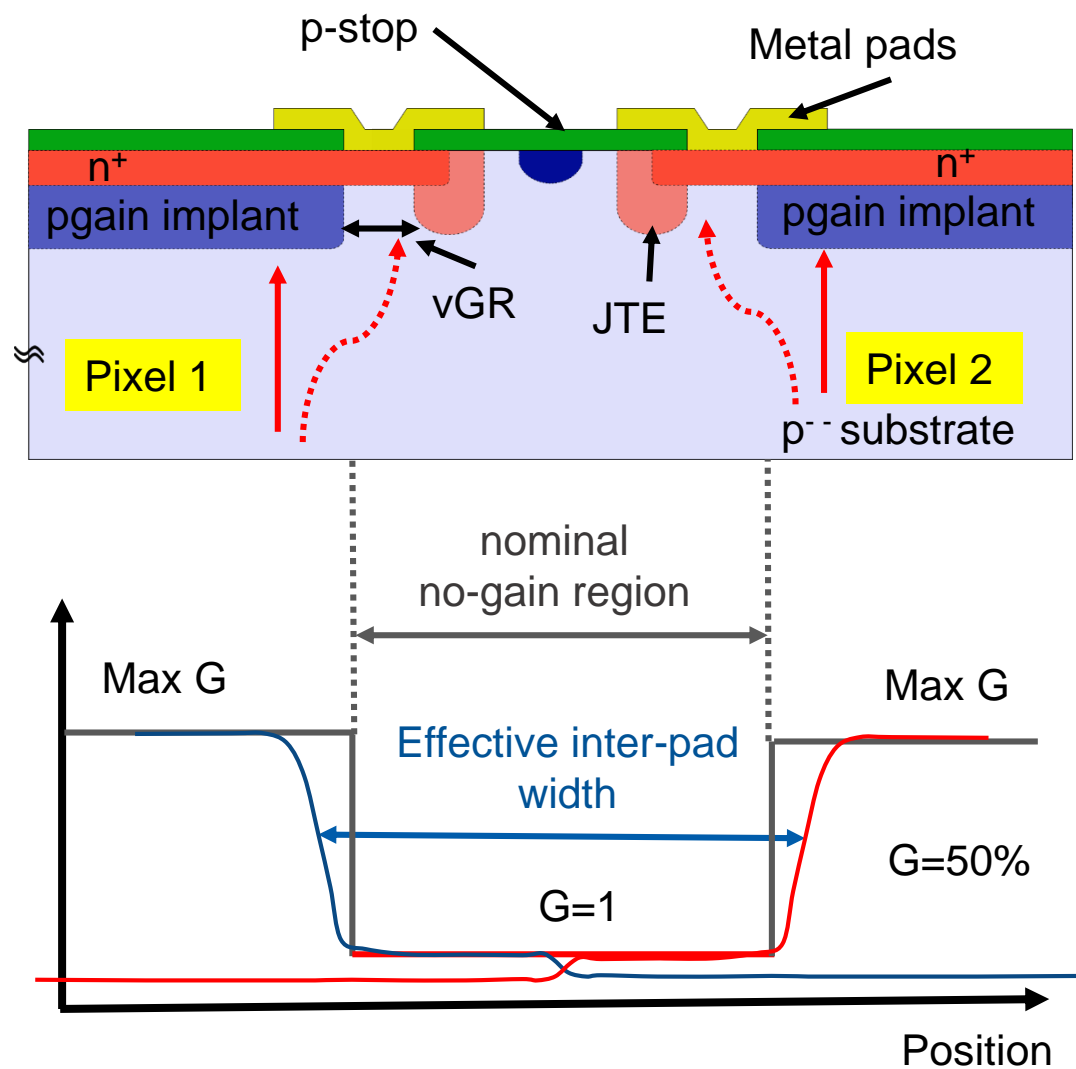


[Ryan Heller, 38th RD50 Workshop]

[Gordana Lastovicka-Medin, 38th RD50 Workshop]

LGAD – Fine segmentation (TI-LGAD)

Segmented Standard LGAD

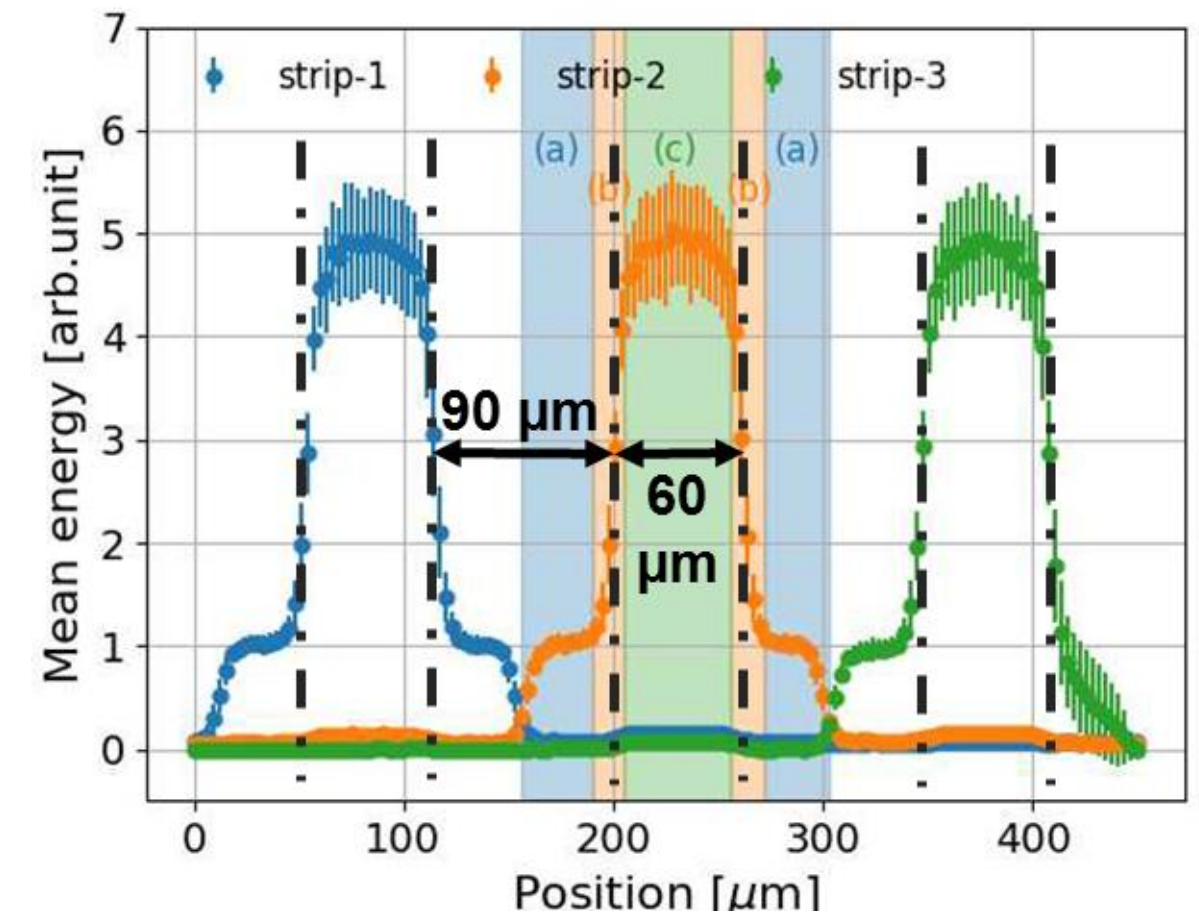


LGADs pixels have limited Fill Factor

- No-gain region at the pixel border due to isolation and termination structures:
 - Dimensions defined by technological and physical constraint
 - Dead distance for charge multiplication ~ 40- 80 μm

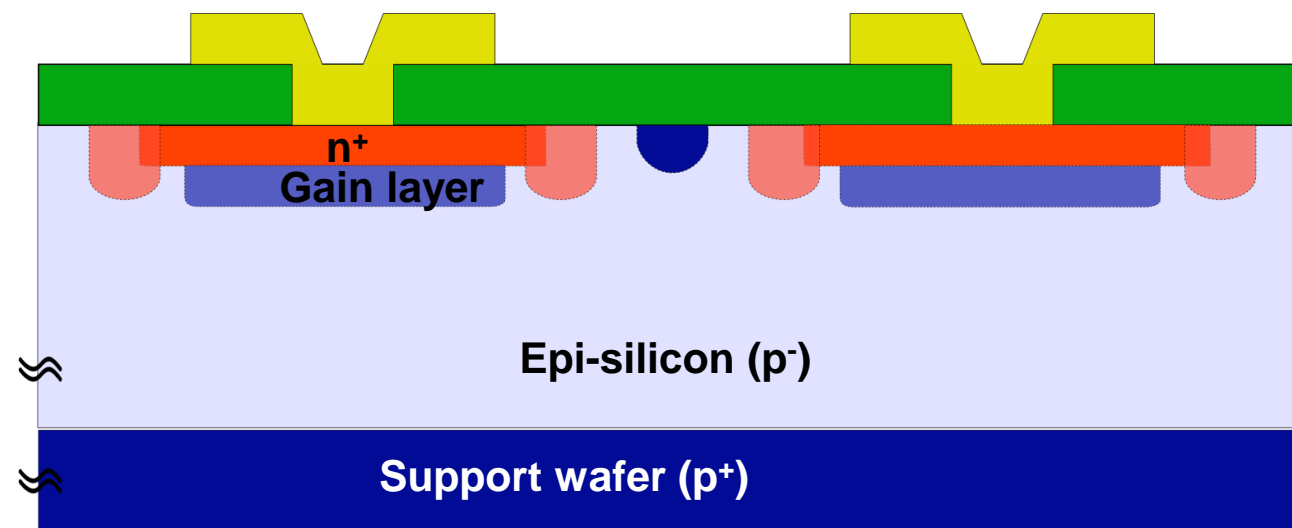
Experimental measurement of LGAD fill-factor using a micro-focused x-ray beam (3 μm , 20 keV) at Swiss Light Source at PSI [5]:

- LGAD micro-strip (146 μm pitch, older UFSD technology)
- Spectrum mean energy as a function of beam position crossing 3 strips
- Nominal FF: 80 μm (55%)
- Measured FF: ~60 μm (40%)

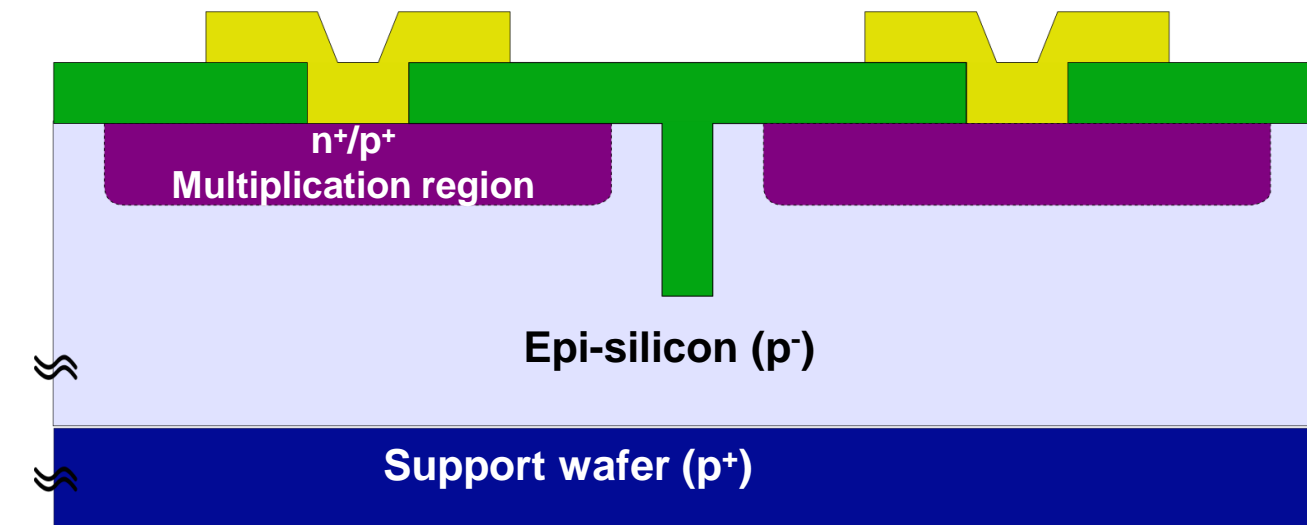


LGAD – Fine segmentation (TI-LGAD)

Segmented Standard LGAD

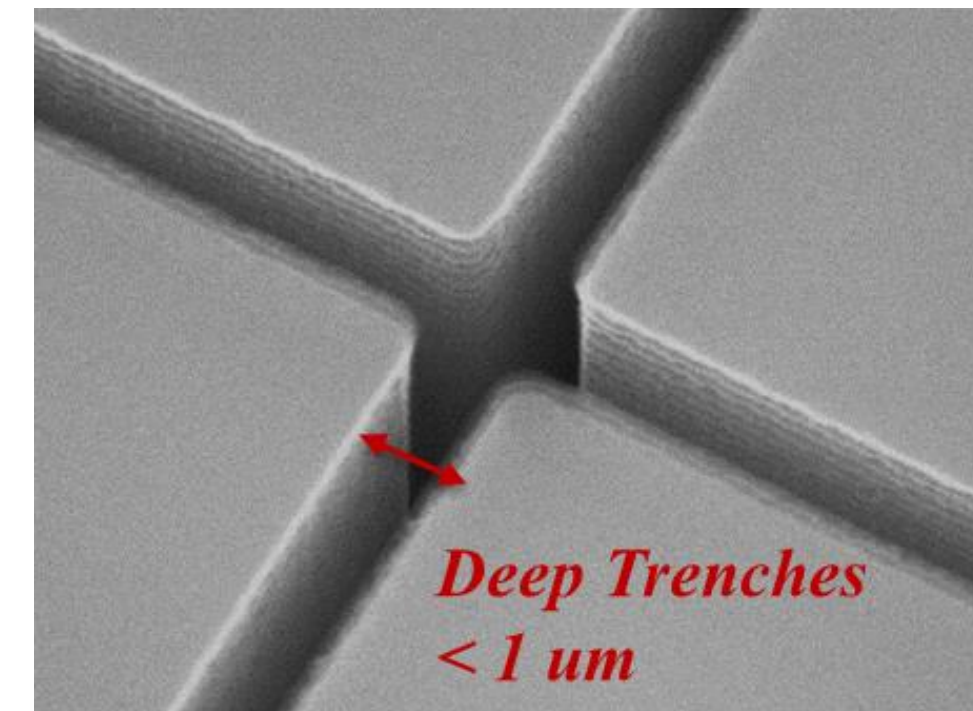


Trench-Isolated LGAD



New **TI-LGAD** technology proposed by FBK:

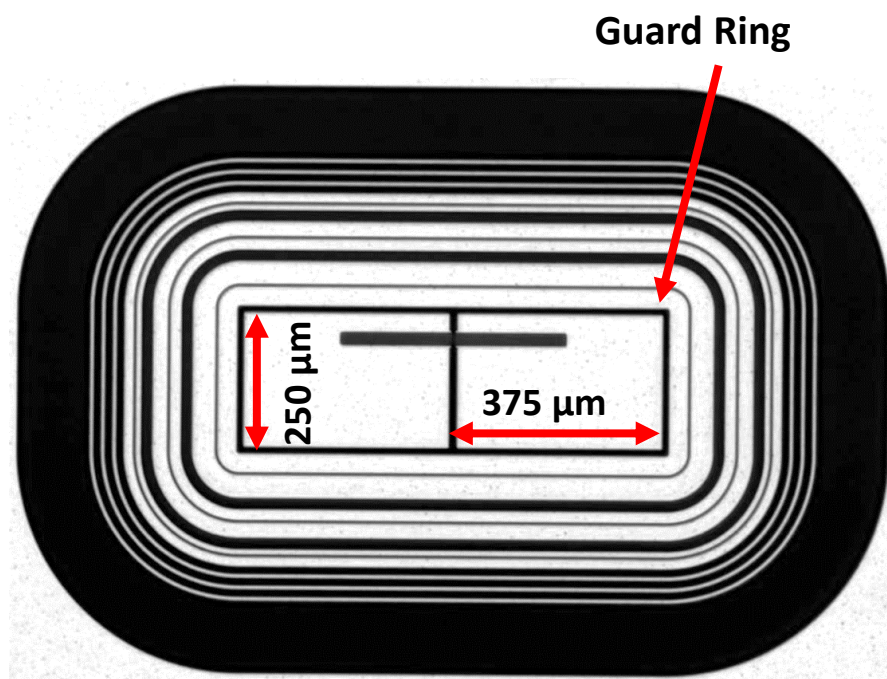
- **JTE and p-stop are replaced by a single trench.**
- Trenches act as a drift/diffusion barrier for electrons and isolate the pixels.
- The trenches are a few microns deep and $< 1\mu\text{m}$ wide.
- Filled with Silicon Oxide
- The fabrication process of trenches is compatible with the standard LGAD process flow.



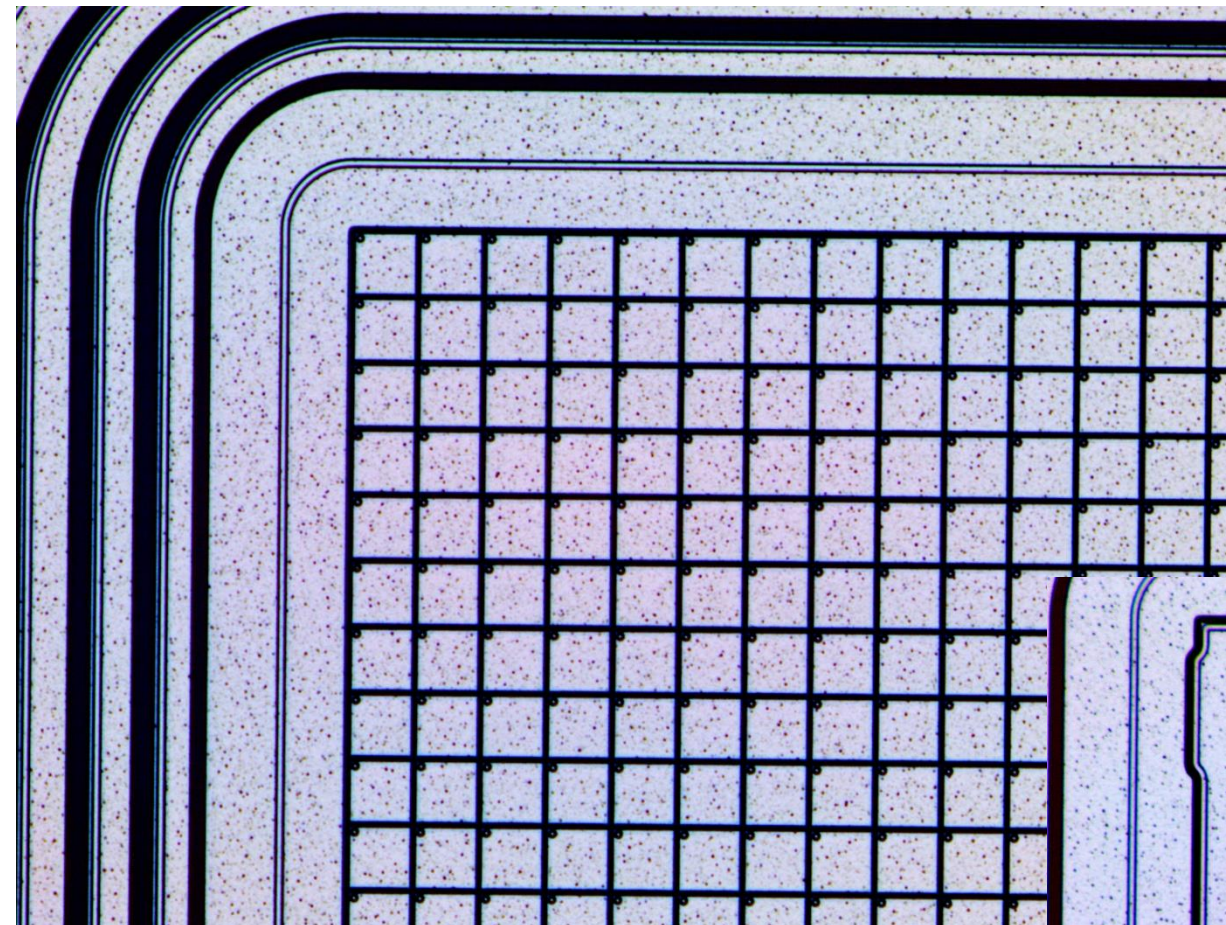
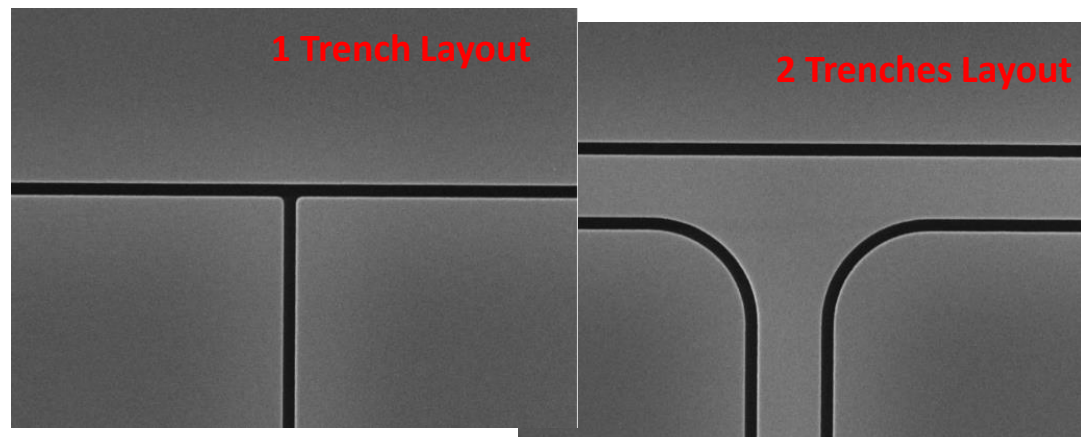
LGAD – Fine segmentation (TI-LGAD)



New RD50 Batch



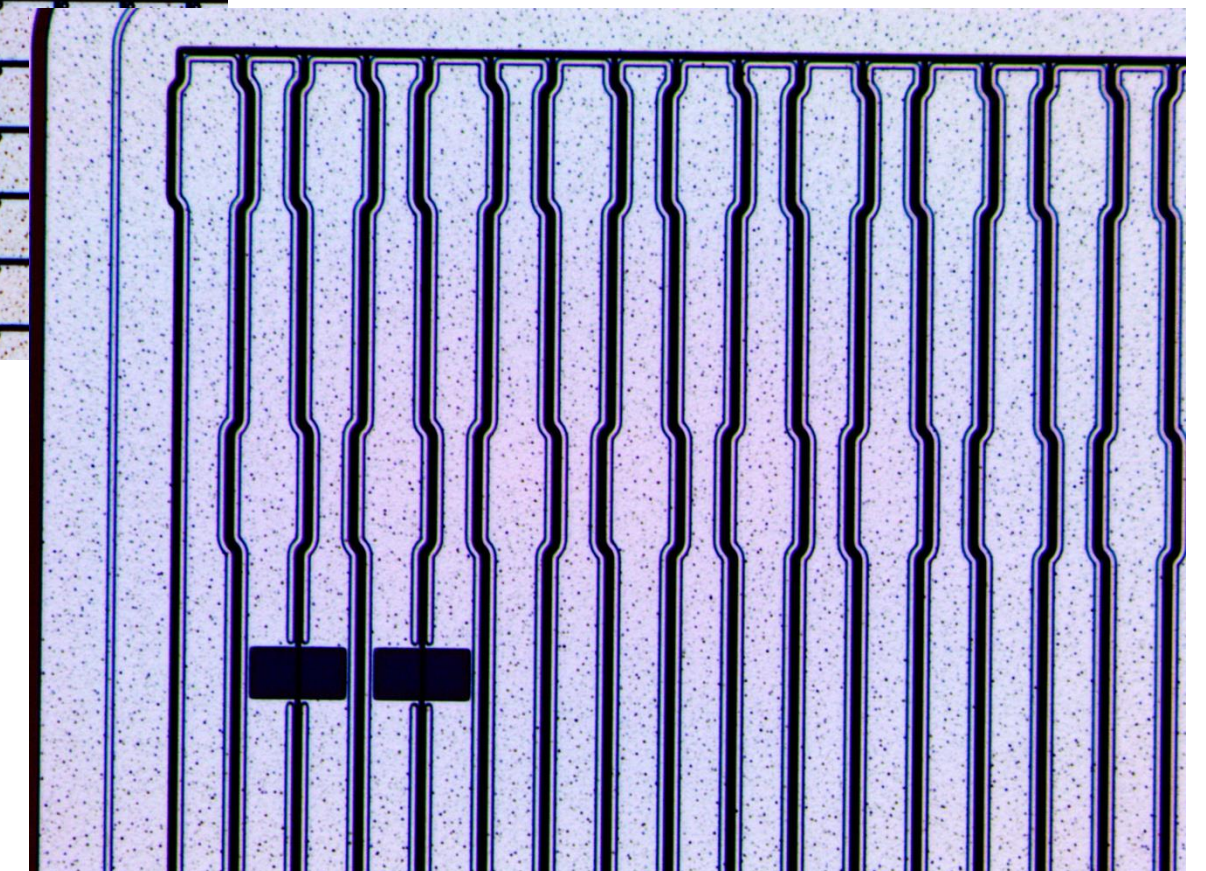
SEM images after trench etching



Nominal FF > 80%

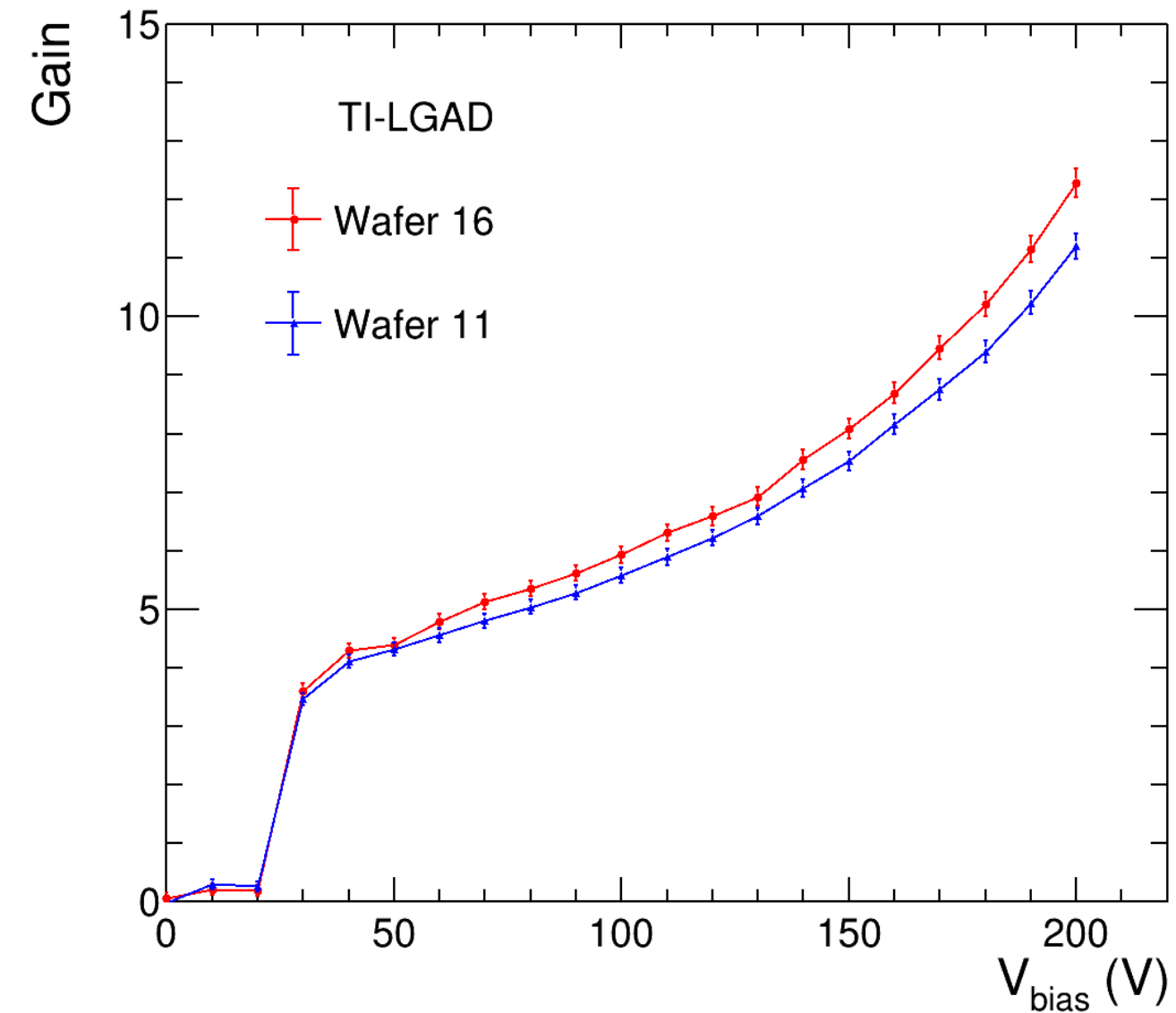
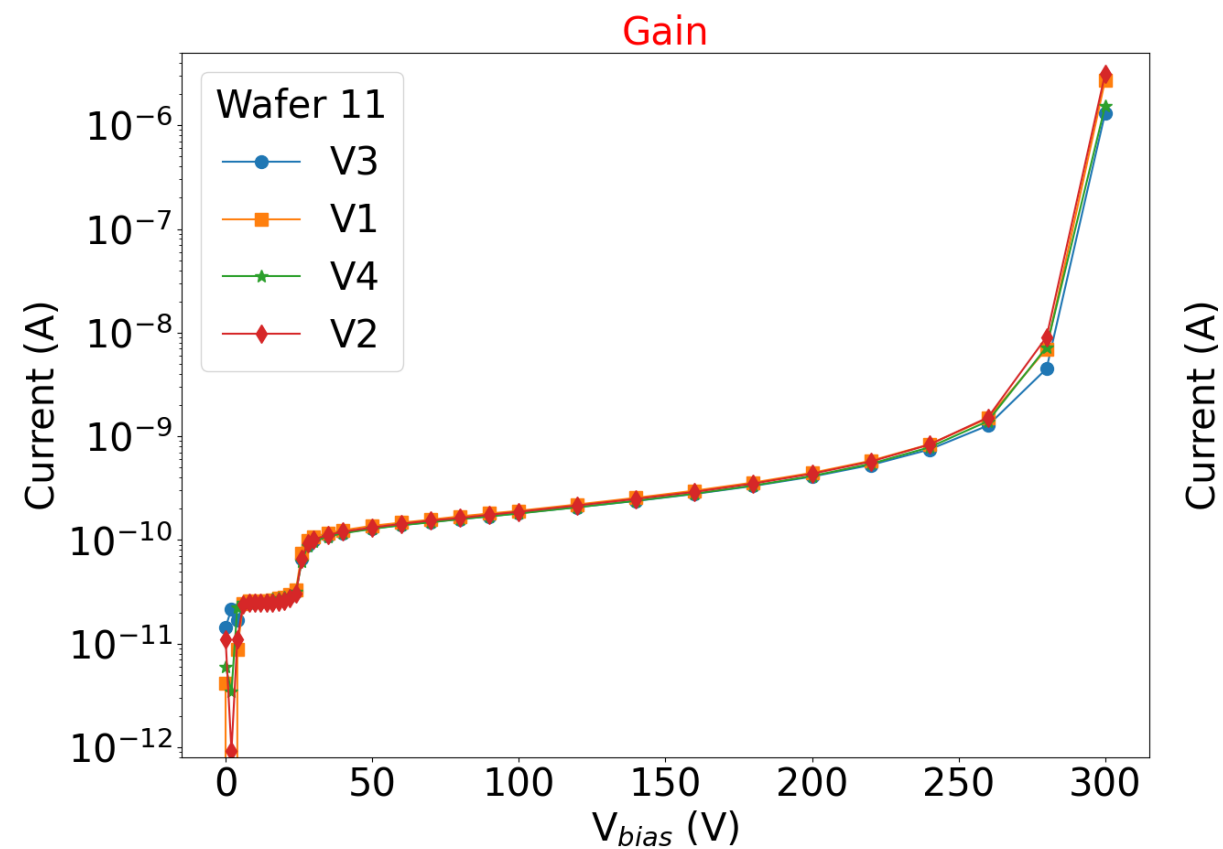
55um Pixels

50-100 um strips



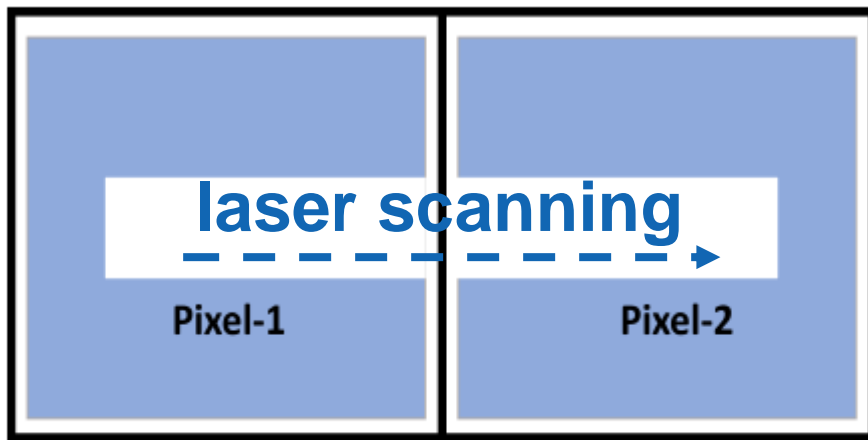
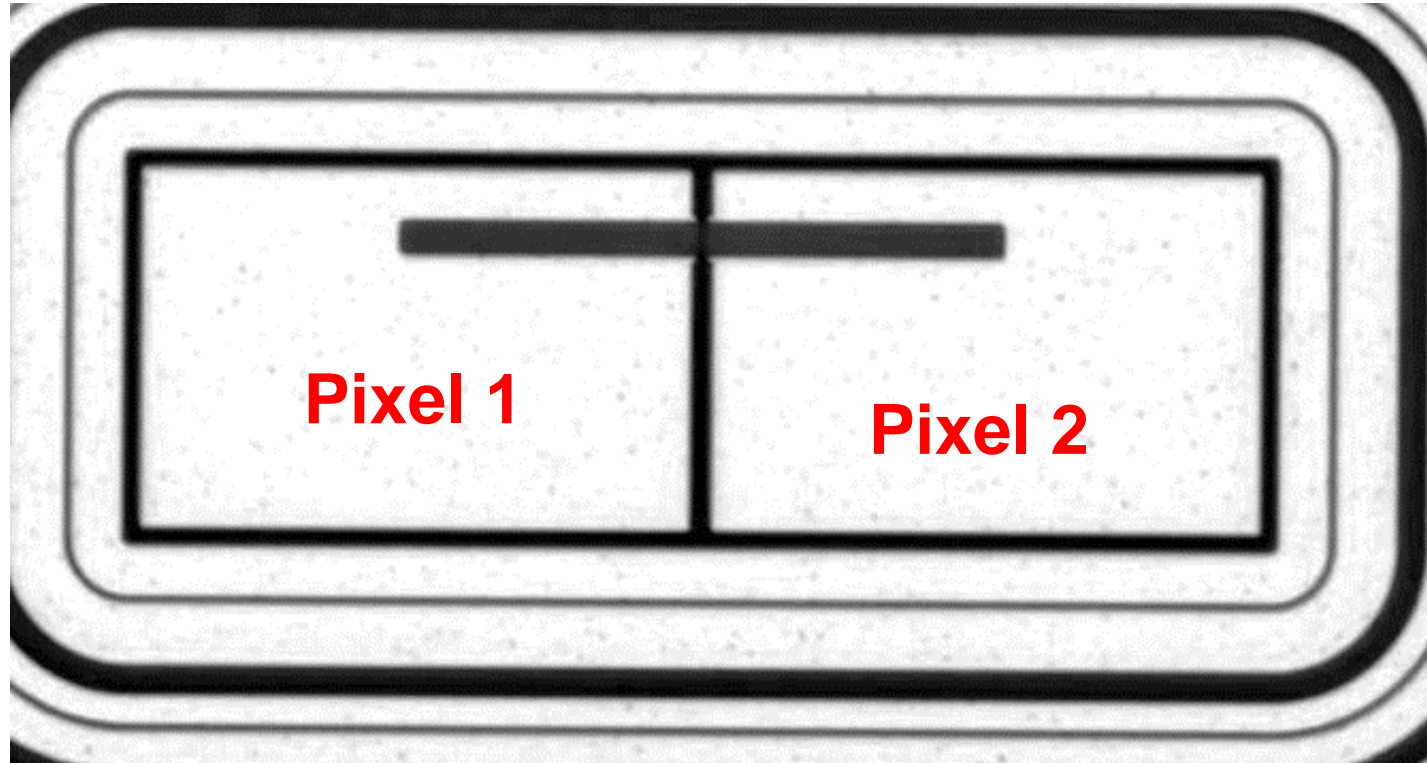
LGAD – Fine segmentation (TI-LGAD)

- IV curves show expected behaviour of TI-LGADs and PiN diodes.
- TI-LGADs: Gain\knee" 25 V / Breakdown > 250
- ! LGAD breakdown is due to gain layer

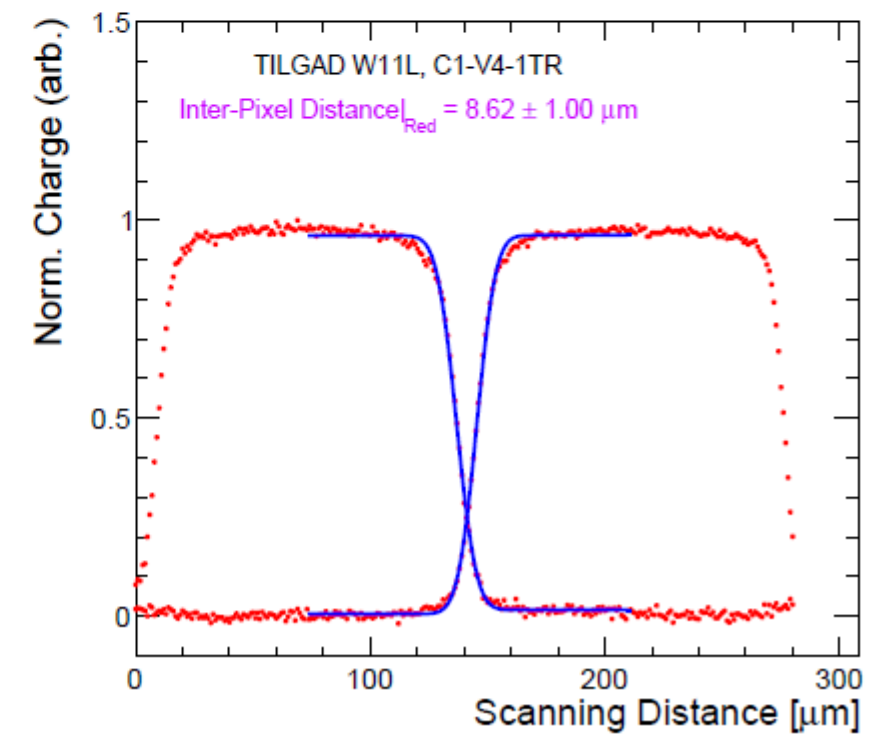
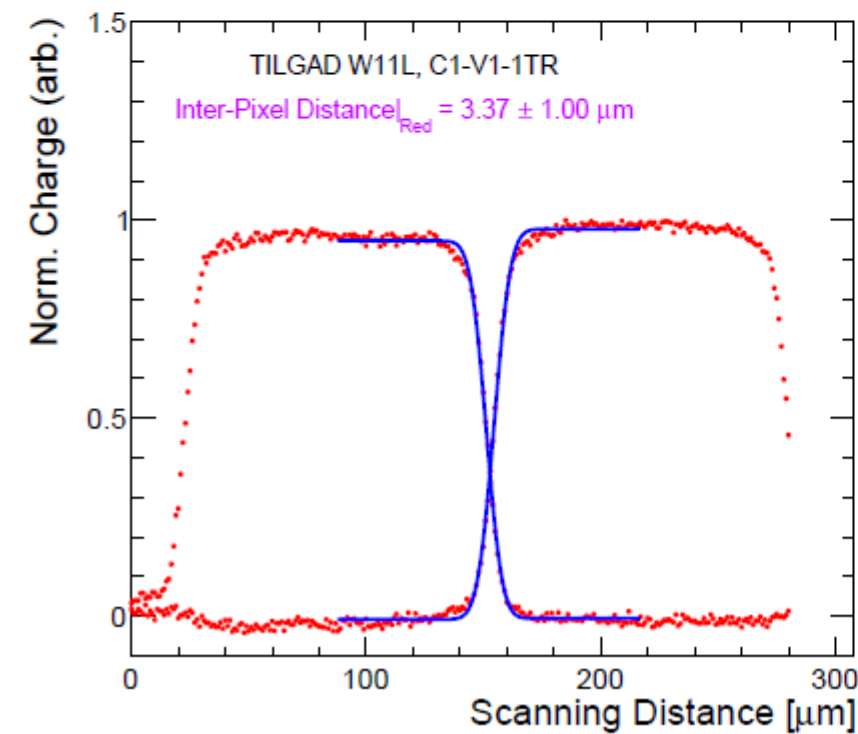
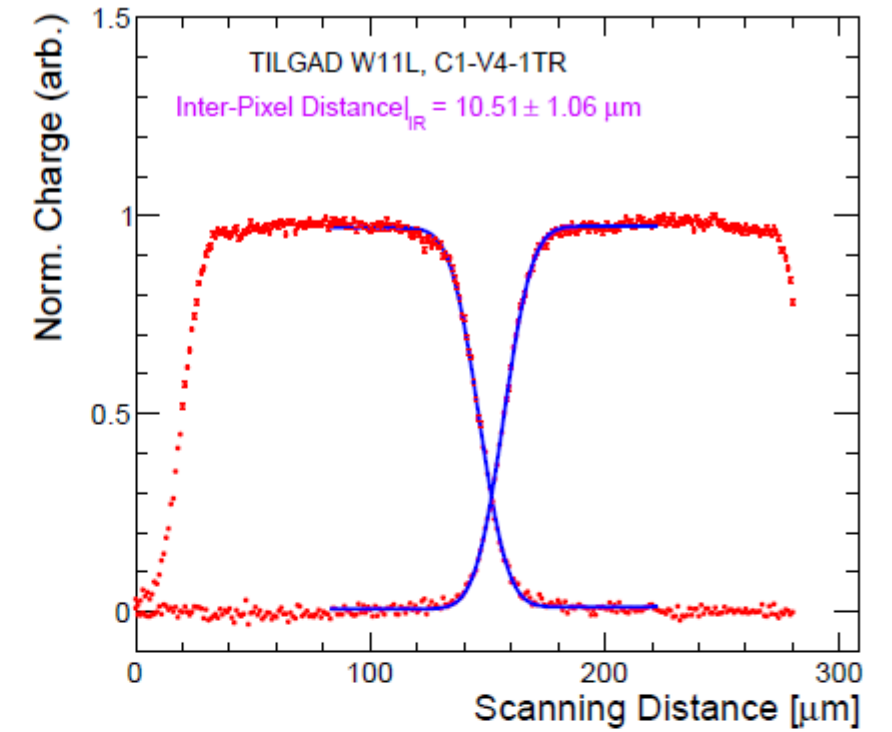
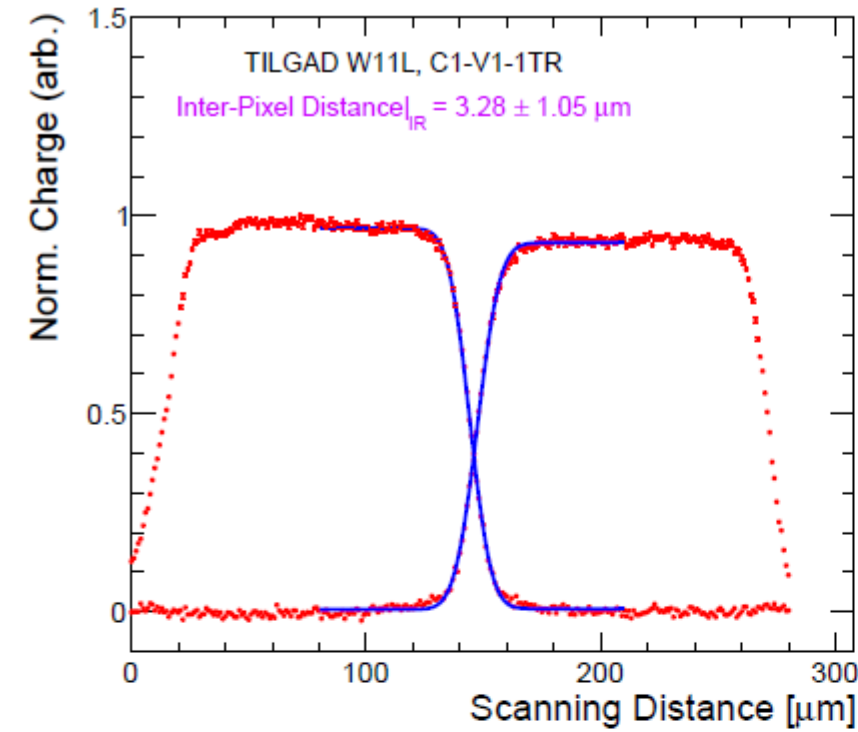


LGAD – Fine segmentation (TI-LGAD)

Inter-pad characterization

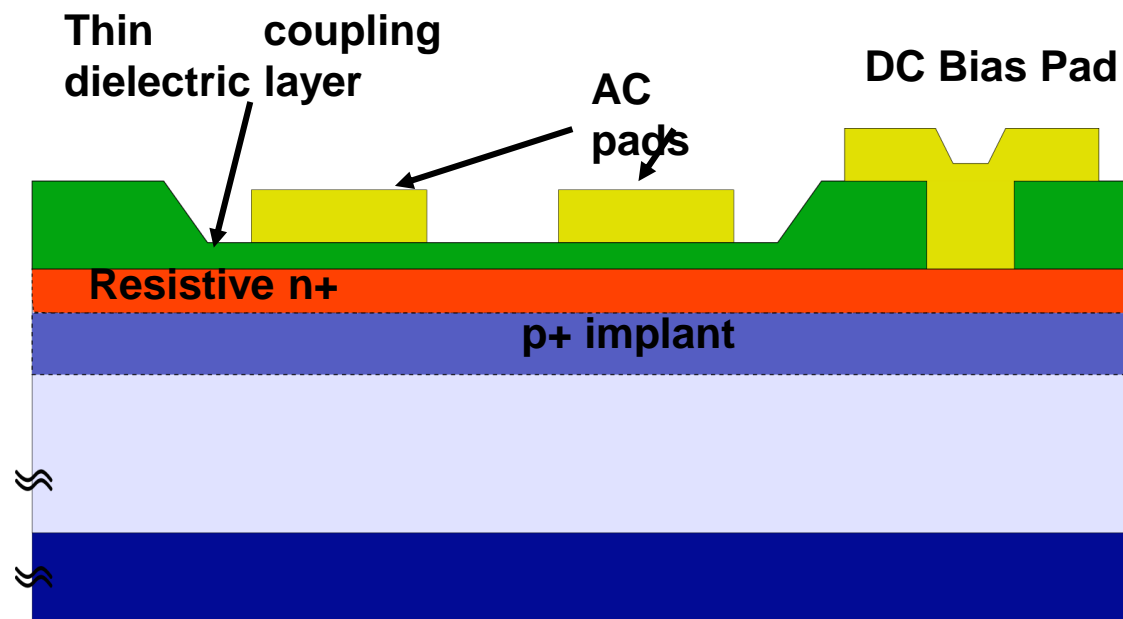


Interpixel distance in the range 3-10 μm (depending on the layout split) x10 times lower wrt standard LGAD



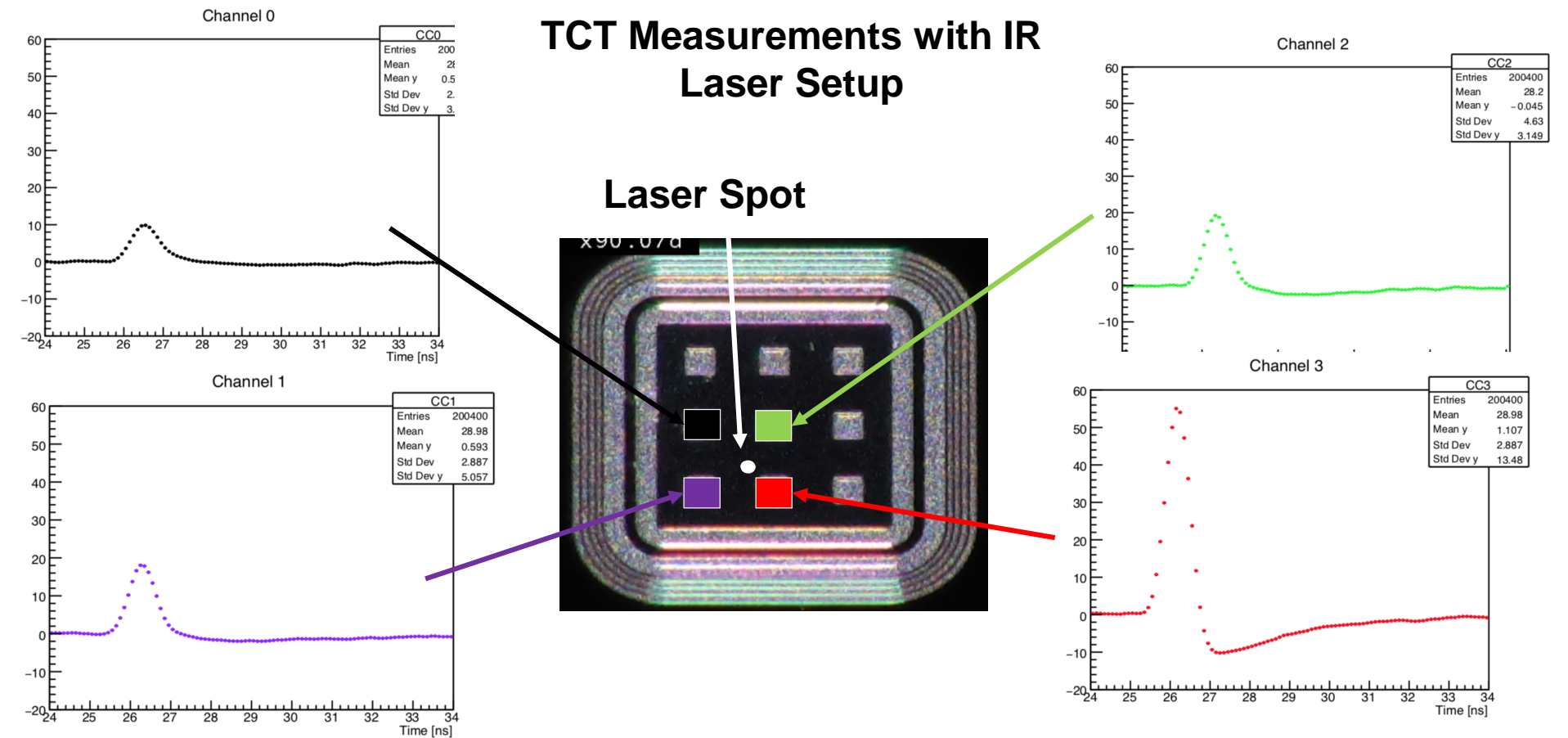
LGAD – Fine segmentation (RSD)

N. Cartiglia



Main Technological Features

- Not-segmented p-gain implant
- Resistive n+ implant
- AC Metal pads
- Segmentation of the AC pads defines the pitch
- Thin coupling dielectric layer under the AC pads



The signal spreads on several pads, with **amplitude inversely proportional to the hit distance**

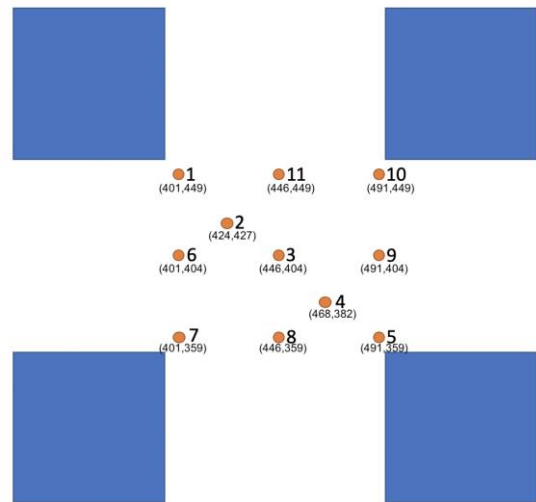
Note: the amplitudes on far away pads is much larger than what is predicted by direct induction

LGAD – Fine segmentation (RSD)

Space Resolution

The position of the hit is obtained as:
(amplitude > 10 mV)

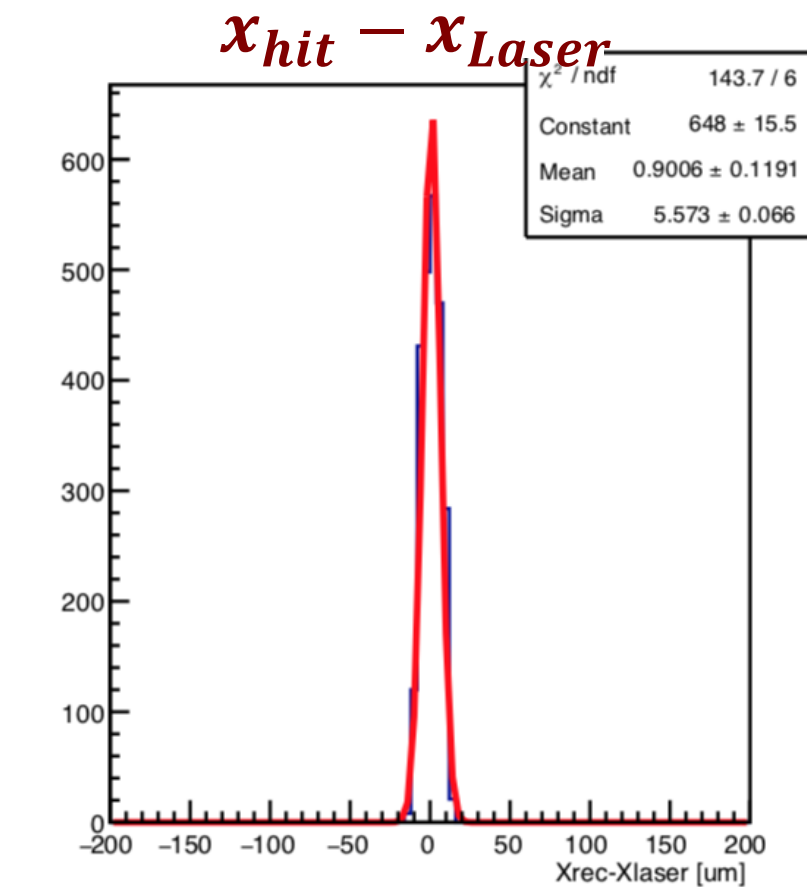
$$x_{hit} = \frac{\sum_{i=1}^{i=4} x_{pad}(i) * Amp(i)^{Cor}}{\sum_{i=1}^{i=4} Amp(i)^{Cor}}$$



100um pitch Array:

x resolution: 6 um, with an offset of 1 um

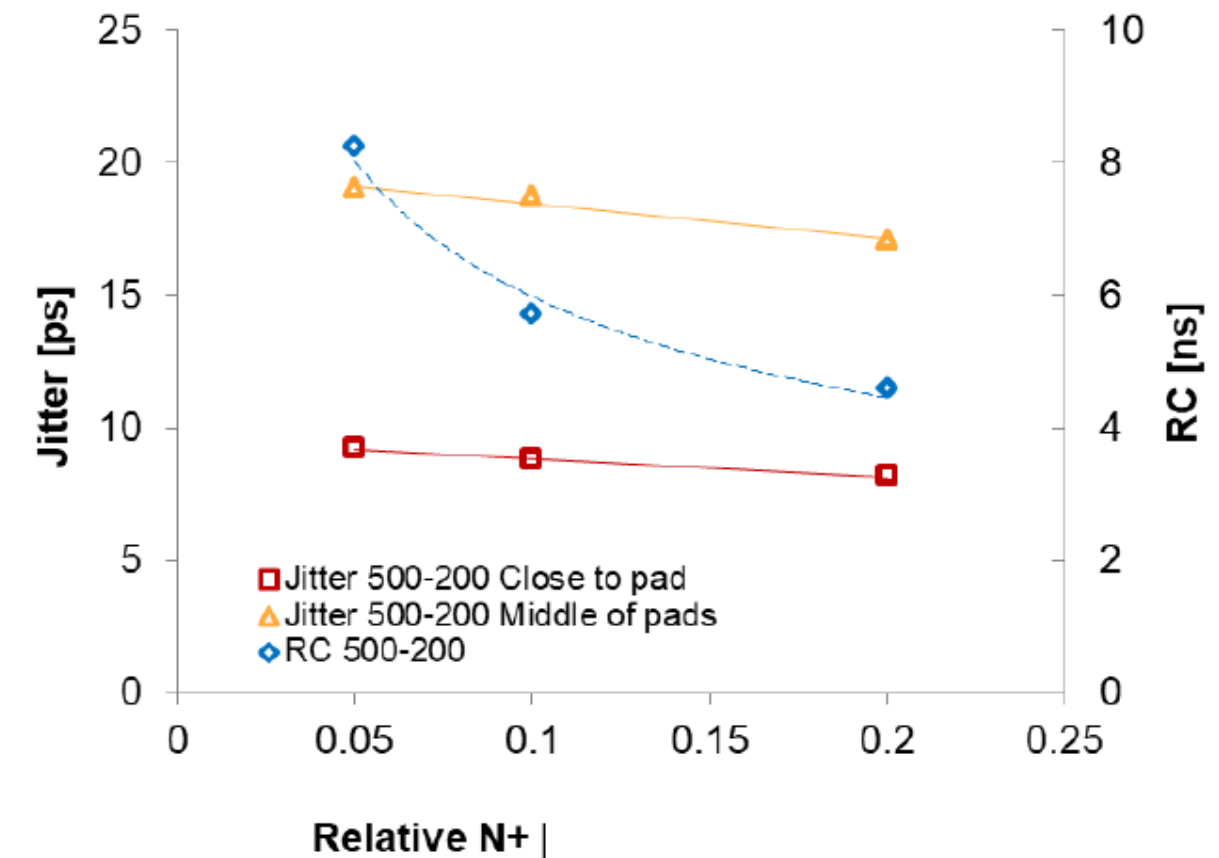
N. Cartiglia



PITCH	x resolution [um]	Y resolution [um]
100 um	4-6	4-6
200 um	6	6
500 um	19	18

Time Resolution

Jitter and RC 500-200 vs N+

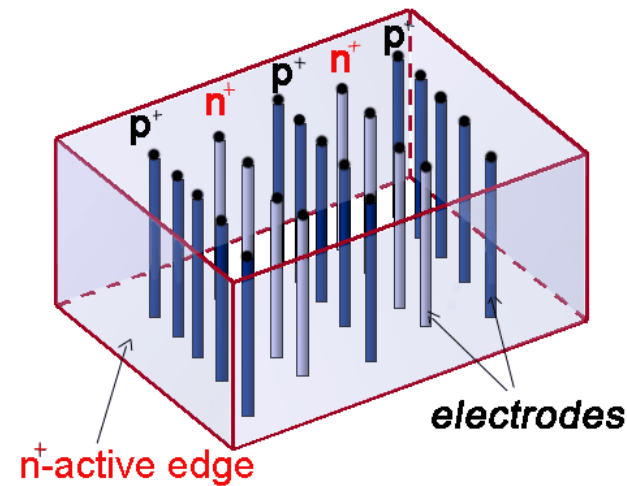


A. Sadrozinski

3D Detectors

3D Detectors

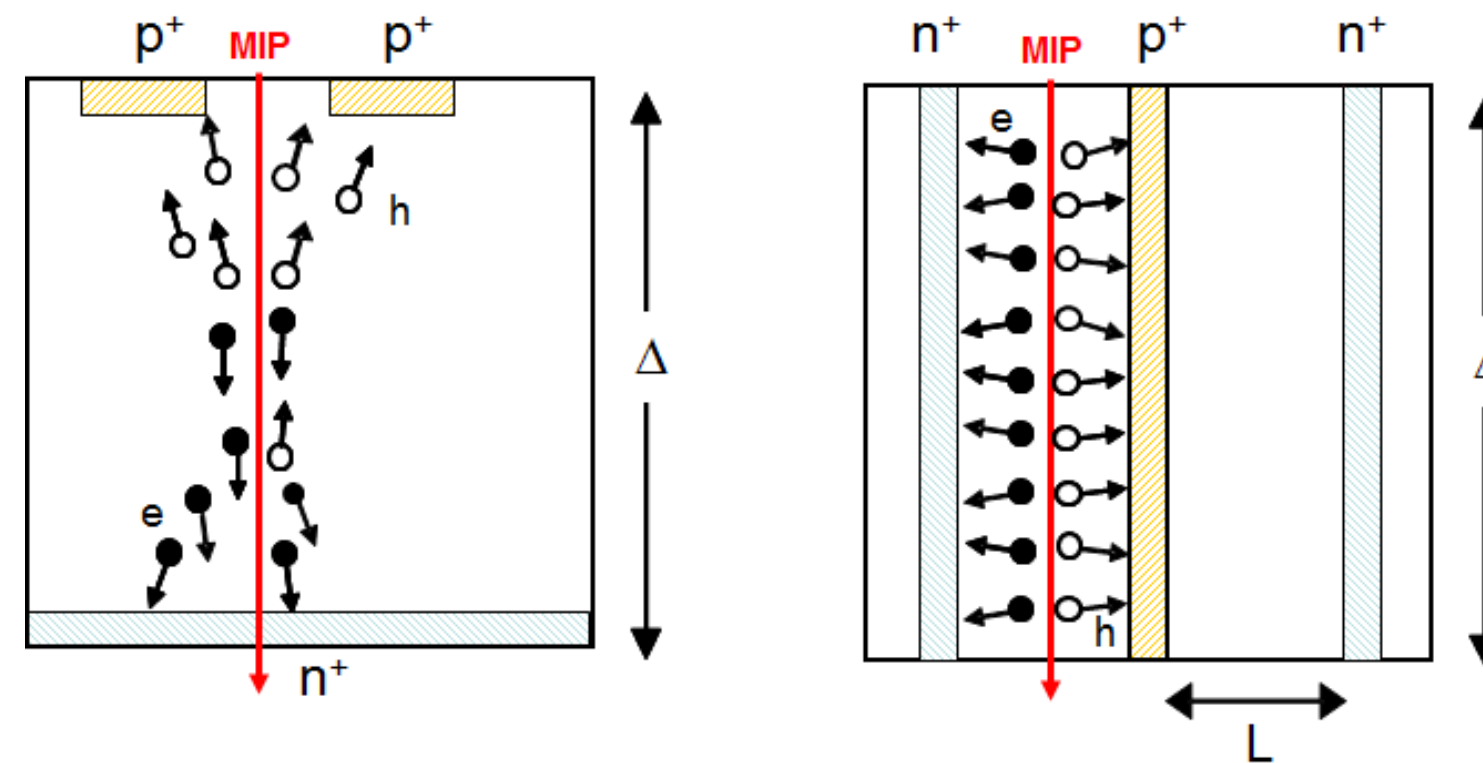
S. Parker et. al. NIMA 395 (1997) 328



ADVANTAGES:

- Low depletion voltage (low power diss.)
- Short charge collection distance:
 - Fast response rise
 - Less trapping probability after irr. -> **high radiation hardness**
- Lateral drift → cell “shielding” effect:
 - Lower charge sharing

Drift distance (L) and active substrate thickness (D) are decoupled → **L ≪ D by layout**

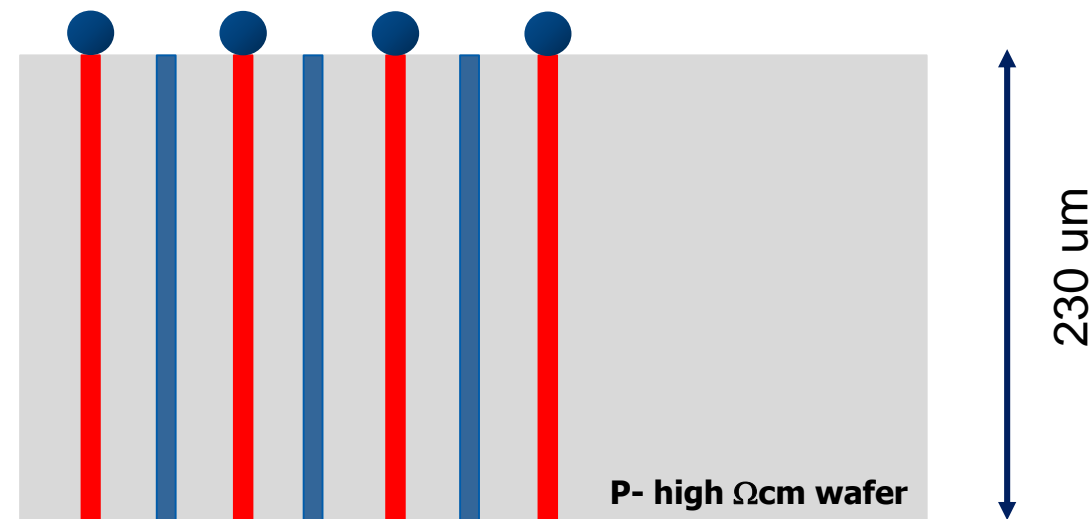


DISADVANTAGES:

- Non uniform spatial response (electrodes and low field regions)
- Higher capacitance with respect to planar (~3-5x for ~ 200 mm thickness)
- **Complicated technology (cost, yield)**

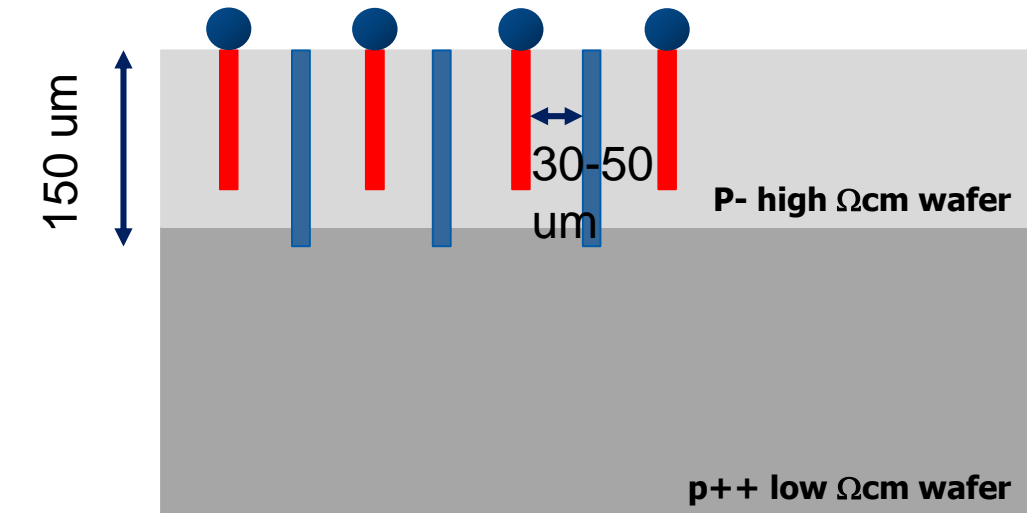
3D Detectors Technology

Double-side 3D, produced by FBK for IBL



- $D = 230 \mu\text{m}$, $L \sim 7 \text{ mm}$, column diam. $\sim 12 \mu\text{m}$
- Excellent performance up to $5 \times 10^{15} n_{\text{eq}} \text{ cm}^{-2}$ also pushed to $\sim 1.4 \times 10^{16} n_{\text{eq}} \text{ cm}^{-2}$ in AFP tests

New single-side 3D technology/design for HL-LHC



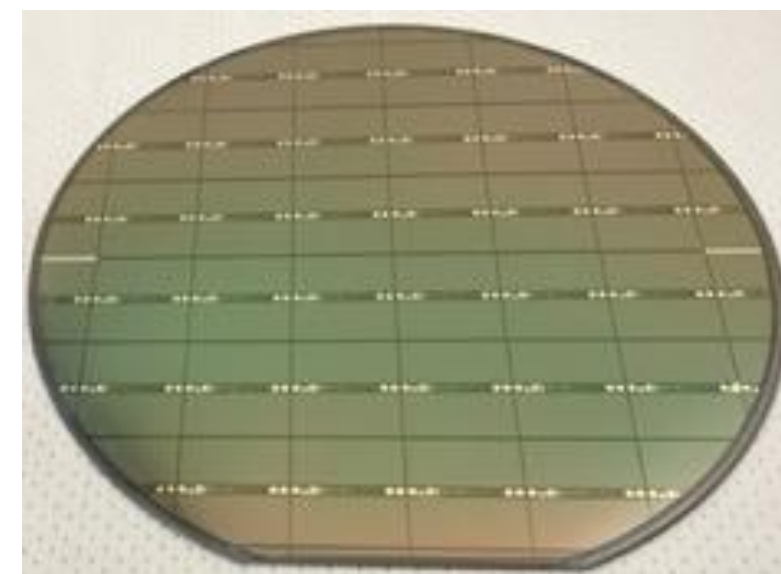
- Thinner sensors (100-150 μm),
- **Narrower electrodes 5 μm**
- reduced inter-electrode spacing ($\sim 30 \mu\text{m}$)

FBK will be one of the lab involved in the realization of 3D Si for HL LHC ATLAS ITK [Lapertosa @ TREDI2021]

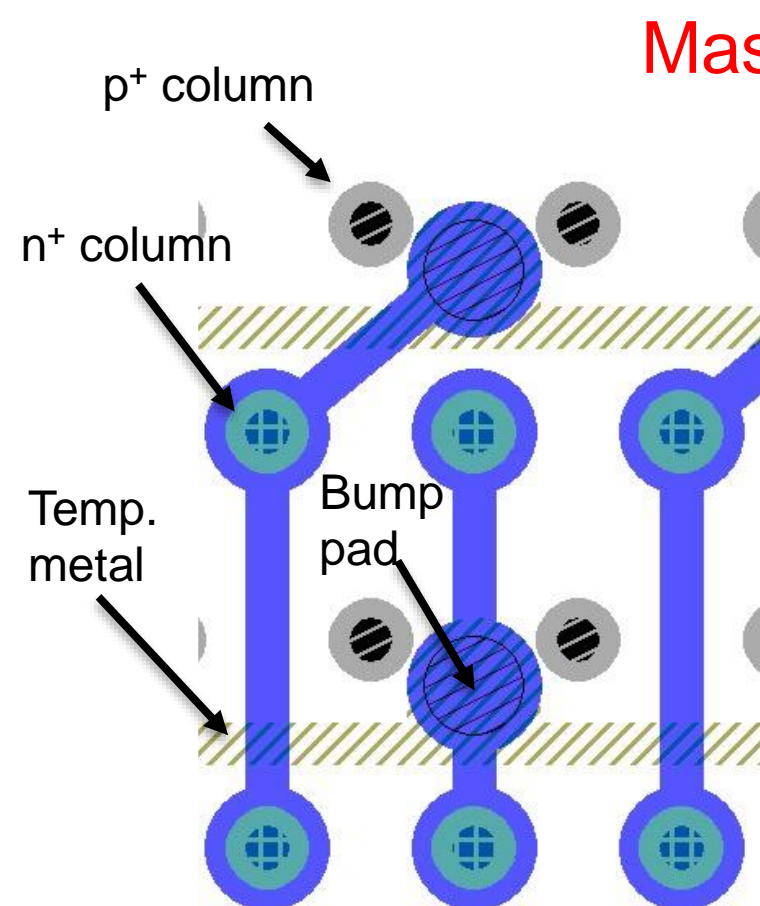
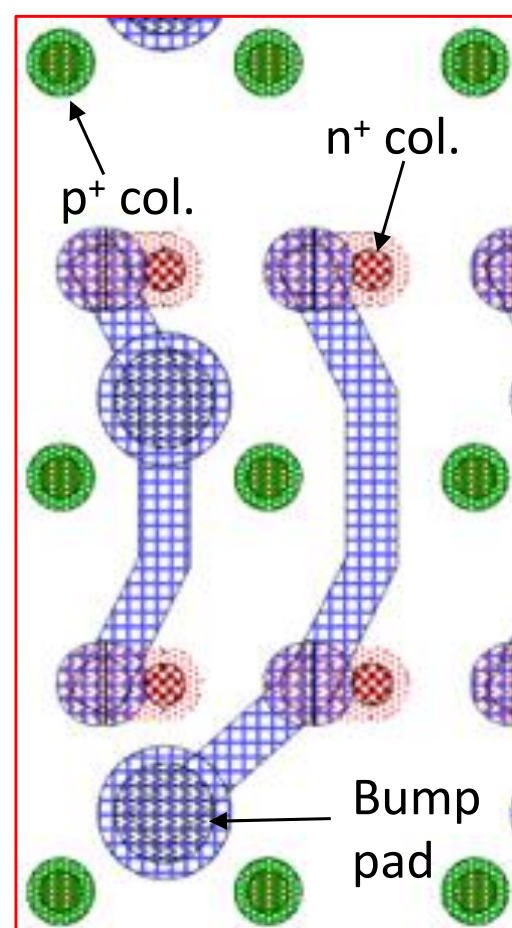
3D Detectors Technology

New single-side 3D technology/design for HL-LHC

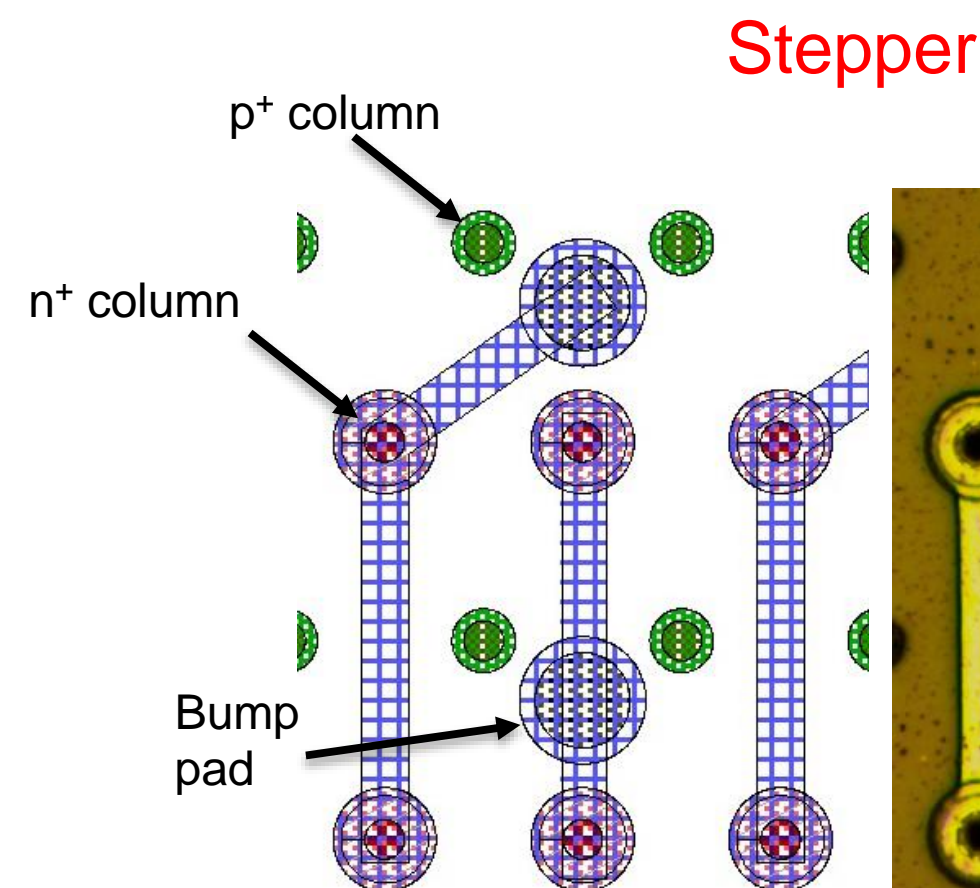
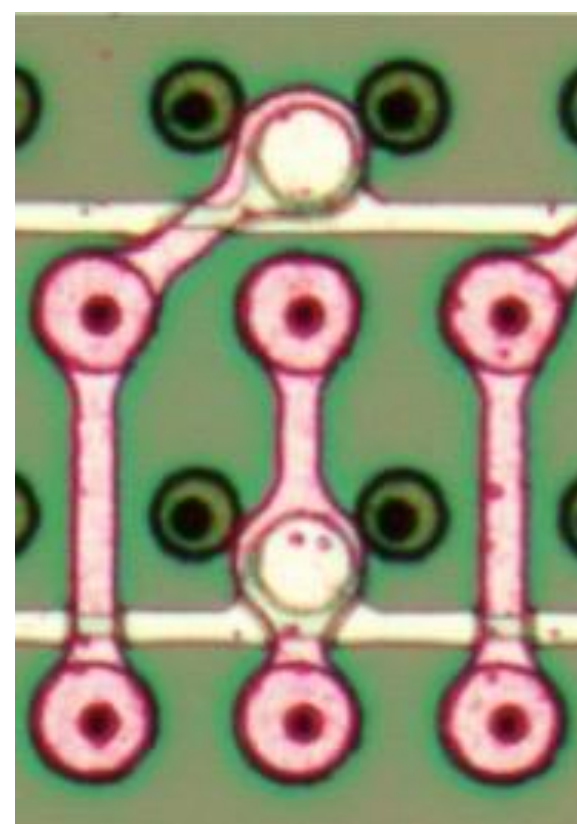
- Mask aligner is not accurate enough for the «25 x 100 – 2E» layout
- Stepper allows for more aggressive layout rules and preserves critical details



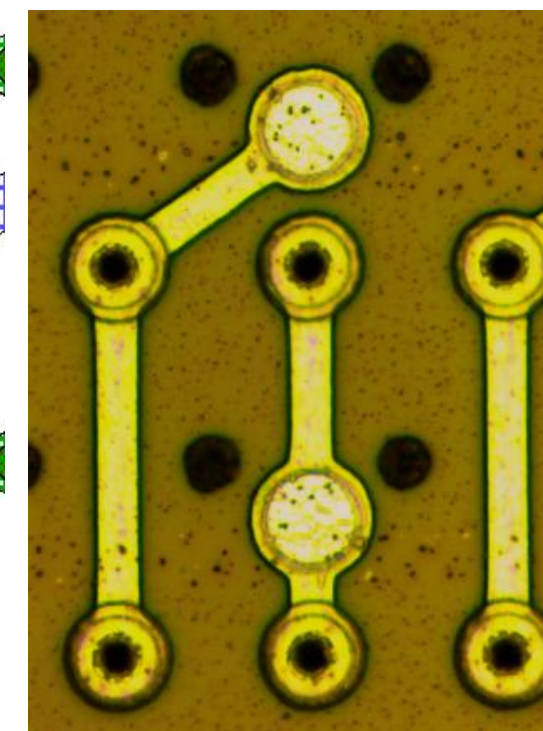
e) 25 x 100 – 2E (H-ear)



Mask Aligner



Stepper



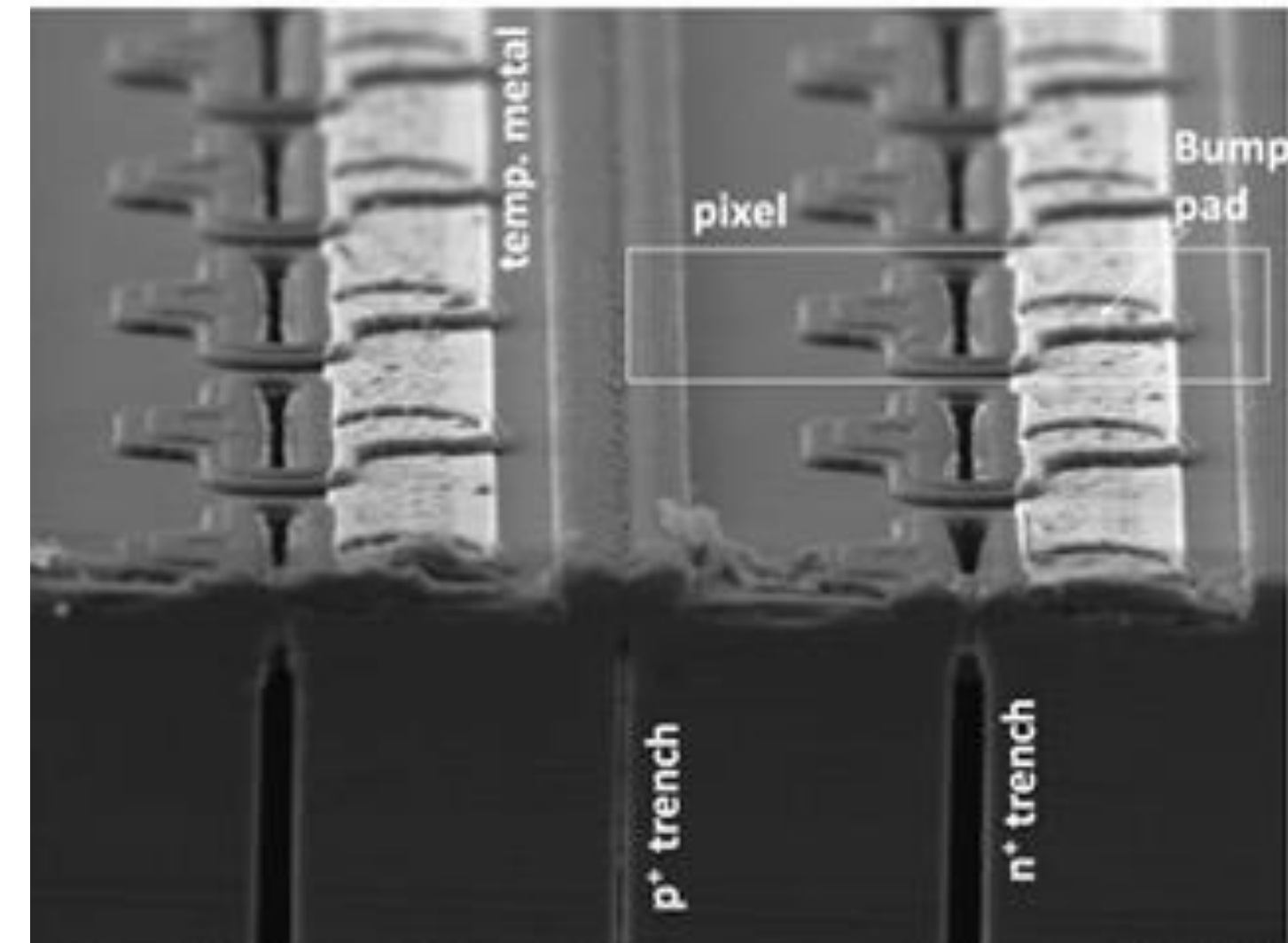
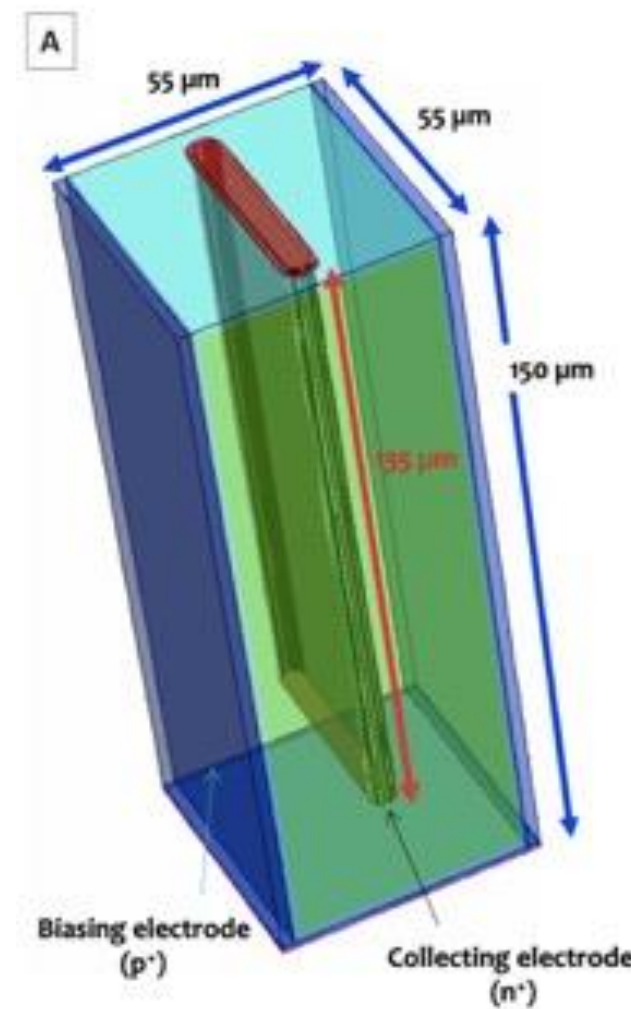
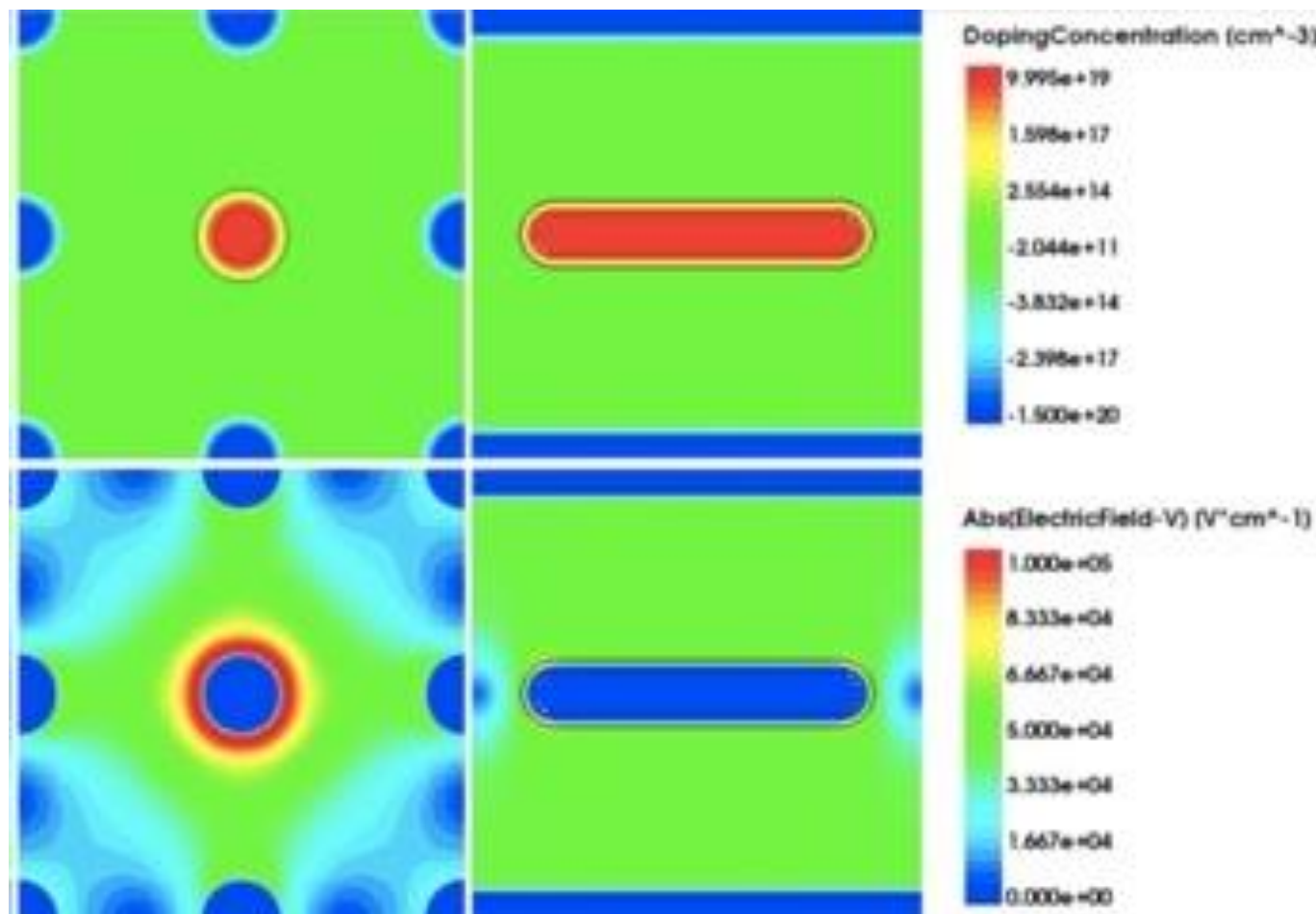
Batch	Yield on full RD53A sensors (%)		
	50x50-1E	25x100-1E	25x100-2E
Mask Aligner	64±23	60±31	19±14
Stepper	58±15	63±18	38±20

3D Detectors for timing

- 3D sensors are also expected to be fast ...
- But layouts with columnar electrodes have non uniform electric and weighting field distributions → go for trenches



See A. Lai talk



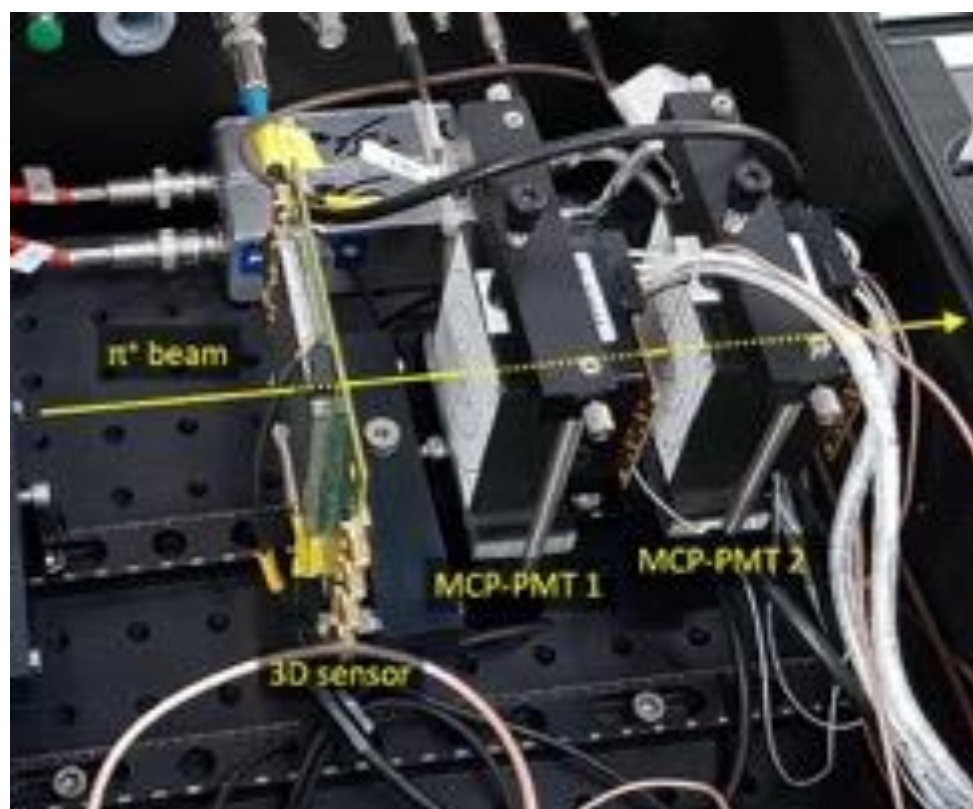
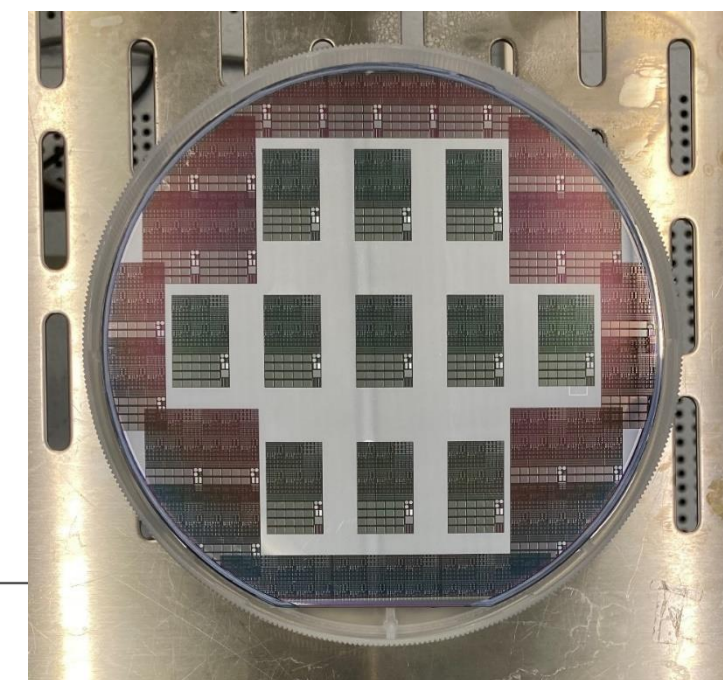
[G.F. Dalla Betta ANNIMA2021]

3D Detectors for timing

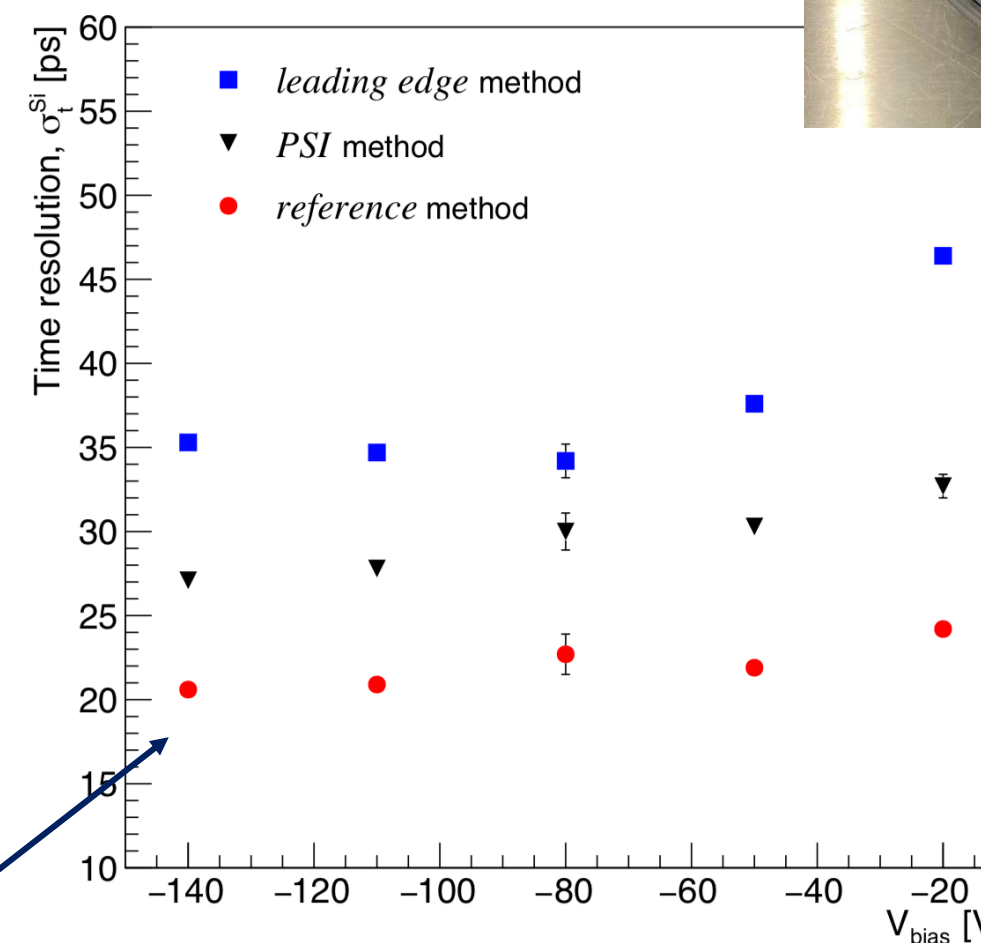
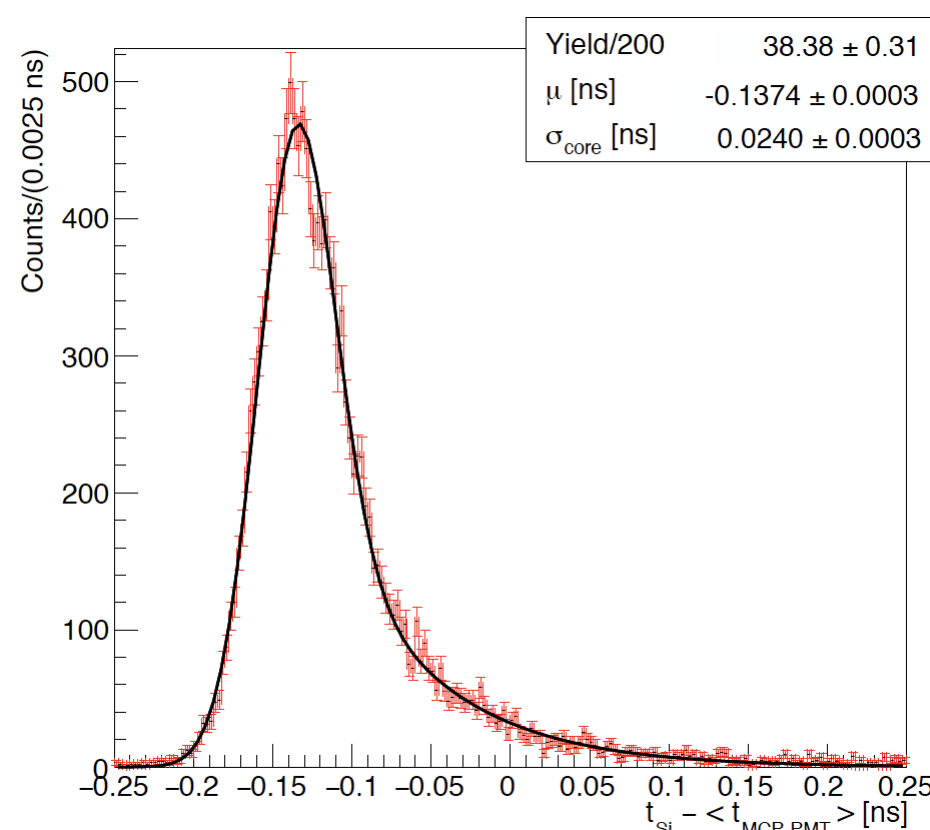


Time resolution of 3D-trench silicon pixels with MIPs (test-beam & lab) at room temperature

(Intrinsic time resolution of 3D-trench silicon pixels for charged particle detection, 2020 JINST 15 P09029)



Beam test @ PSI (10/2019)



$s_t \approx 20 \text{ ps}$

(after correction for MCP contribution) confirmed in corresponding laboratory measurements (with ^{90}Sr source)

[G.F. Dalla Betta ANNIMA2021]

Conclusions

- In the last years FBK developed two technologies of silicon detectors for 4D-tracking with concurrent time and spatial resolution: **LGAD** and **3D**
- Last developments in **LGAD** lead to time resolution $\sim 30\text{ps}$ up to fluences of $2.5\text{e}15$ neq, mainly thanks to the using of thin substrates and initial acceptor removal mitigation
- New developments for fine-segmented LGADs are ongoing: **RSD** and **TI-LGADs** providing high FF and high spatial resolution
- Latest developments on **3D detectors** allowed to improve the technology (minimum CD & yield)
- 3D detectors shown an intrinsic **high radiation resistance** up to $1\text{e}16$ neq
- 3D detectors for timing have been developed in **TimeSpot project**, time resolution down to 20ps has been demonstrated

Thank you for your attention

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